

Electron Energy-Loss Spectroscopy (EELS) – Basics

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EPFL-IPHYS-LSME

EPFL EELS basics: contents

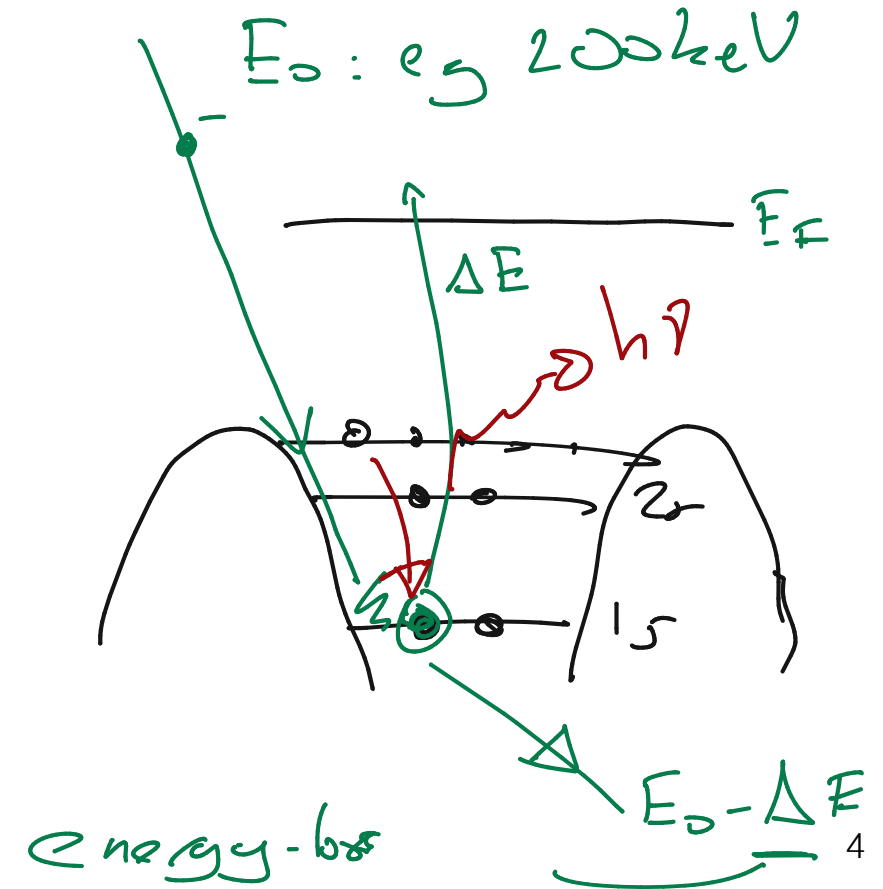
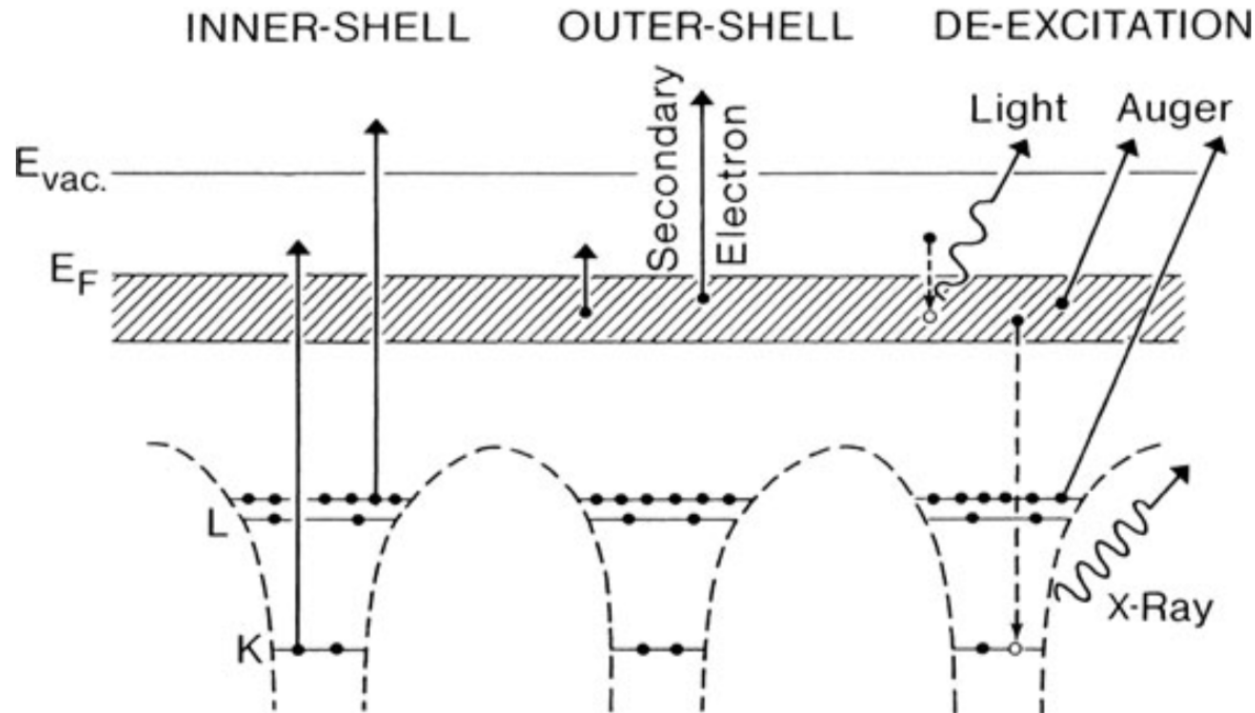
- Ionisation energy loss
- Electron energy-loss spectrometer
- Features of the EEL spectrum
- Ionisation edge Core-loss analysis
 - Elemental detection and mapping
 - Elemental quantification
 - ELNES
- Low-loss EELS
 - Bulk plasmon
 - Multiple scattering, thickness measurement and deconvolution
- EELS spatial resolution
- References

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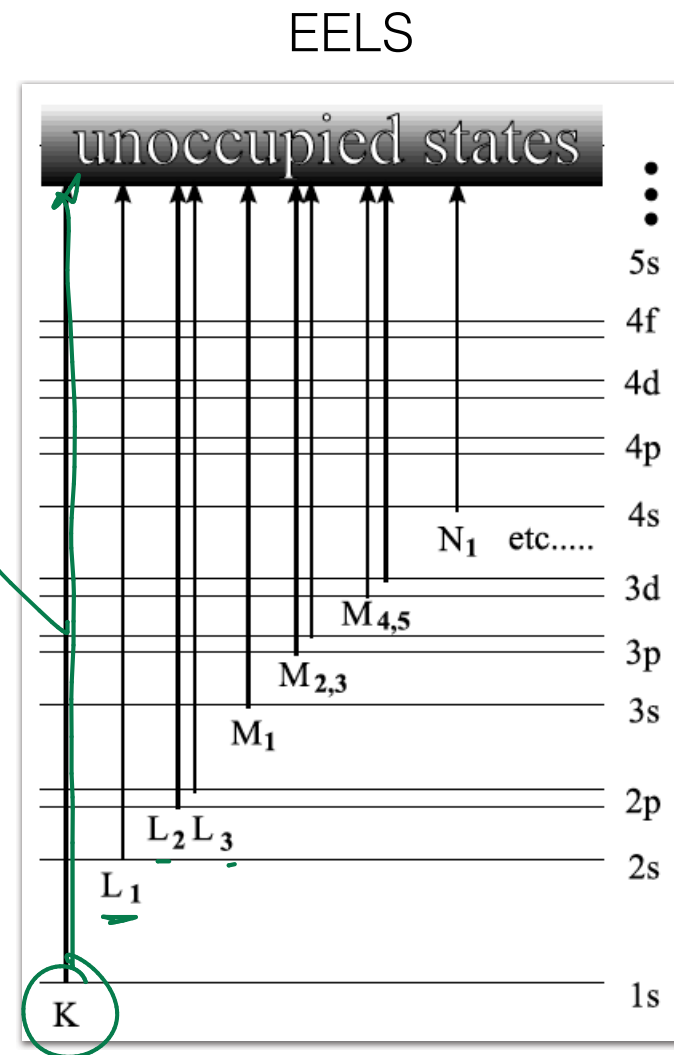
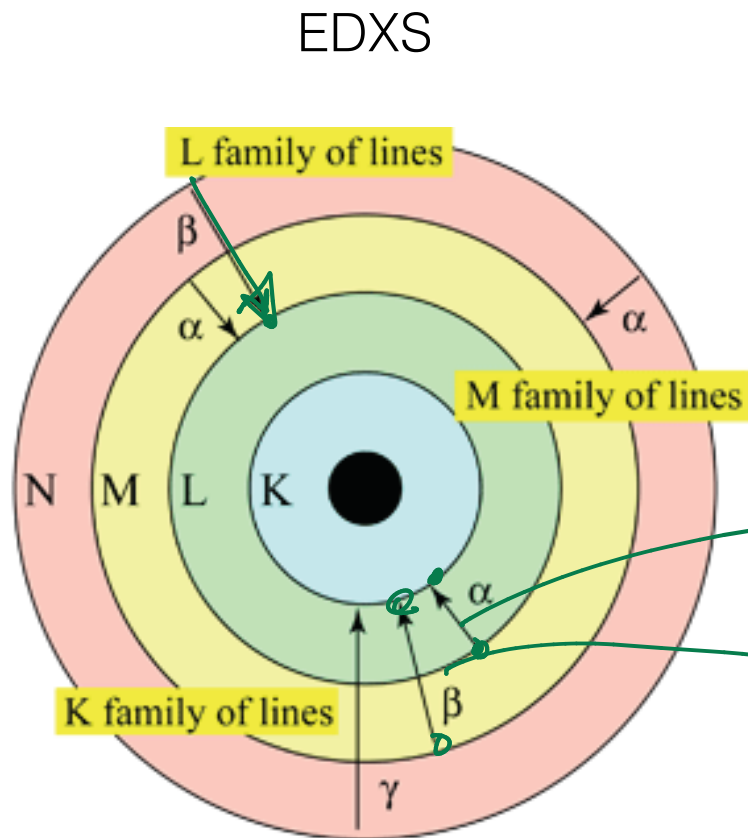
EPFL Ionisation energy loss

- Atomic ionisation leading to X-ray emission $\Leftrightarrow$ energy loss of transmitted e^-



$$\Delta E \quad \kappa > 2$$

$$L_1 > L_2 > L_3$$



energy of $\kappa_\beta > \kappa_\alpha \dots$
- peaks

κ edge

} M edge
} L edge

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EPFL Electron energy-loss spectrometer

- Typical EEL spectrometer: magnetic prism

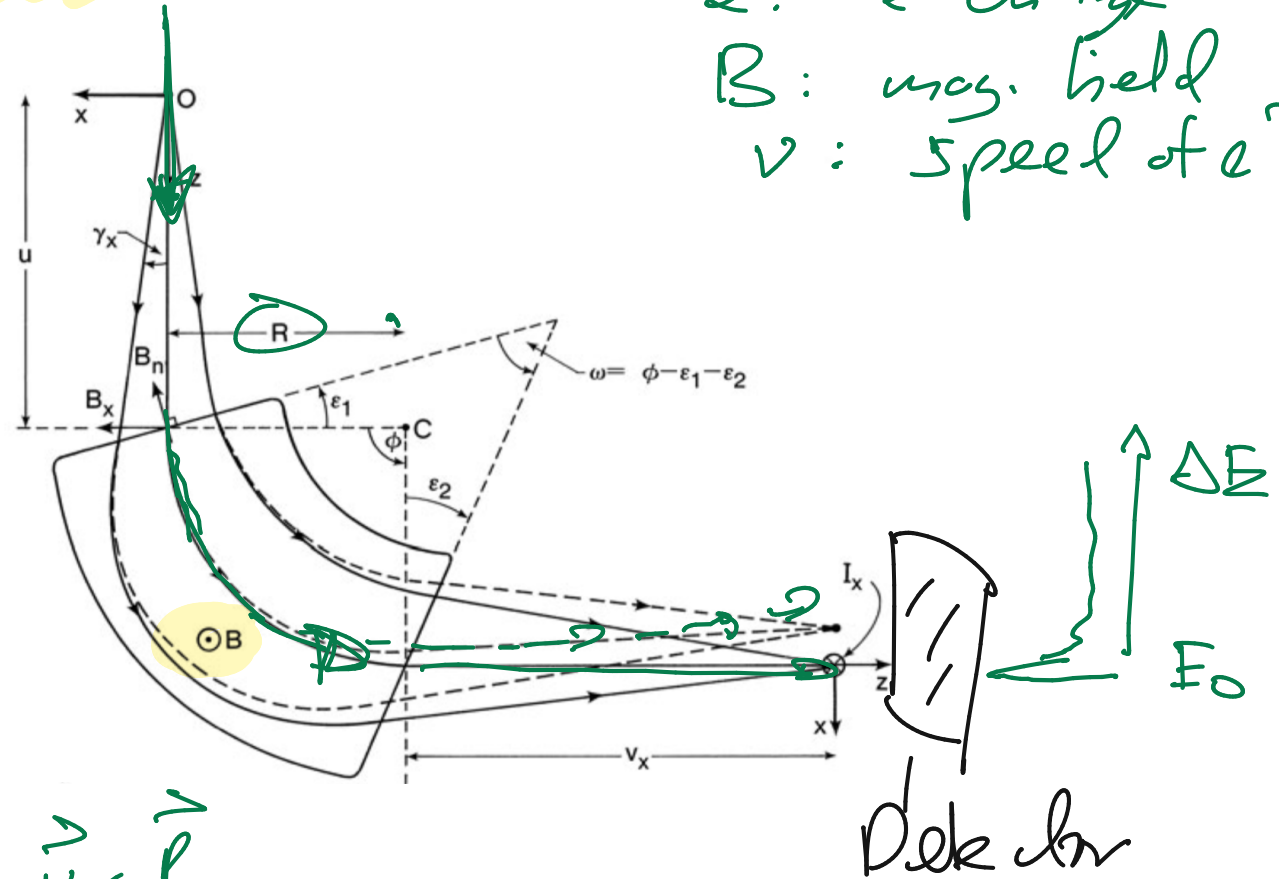
m_0 : rest mass of e^-
 e : e^- charge
 B : mag. field
 v : speed of e^-

$$R = (\gamma m_0 / eB) v$$

$$\gamma = 1 / (1 - v^2 / c^2)^{1/2}$$

Relativistic factor

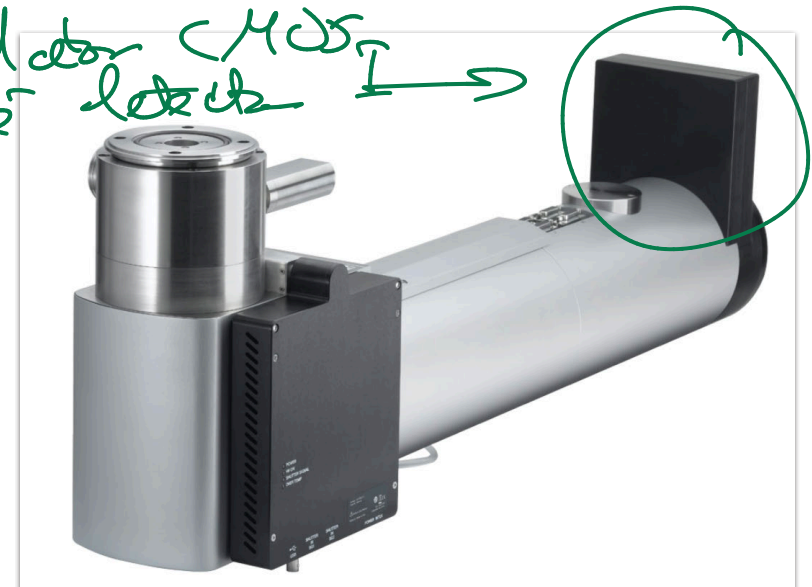
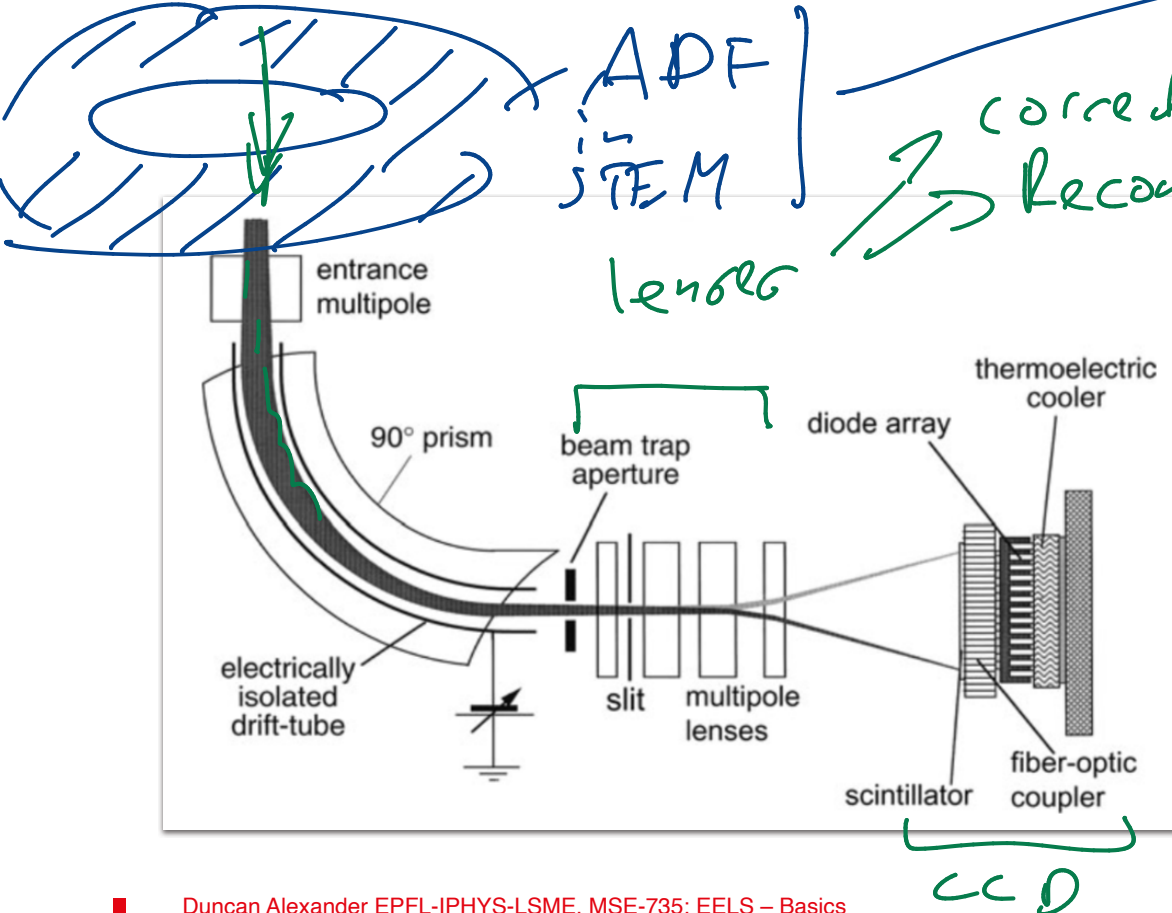
→ Lorentz force: $\vec{F} = e \cdot \vec{v} \times \vec{B}$



EPFL Post-column spectrometer

- Post-column spectrometer most common type used for materials science/physics
- For instance: Gatan Image Filter (GIF)

STEM-EELS



Inelastic scattering angular range

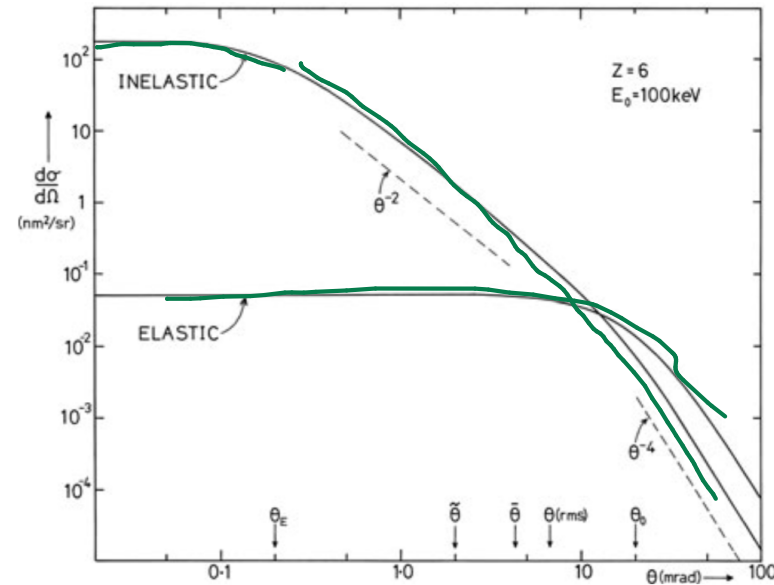
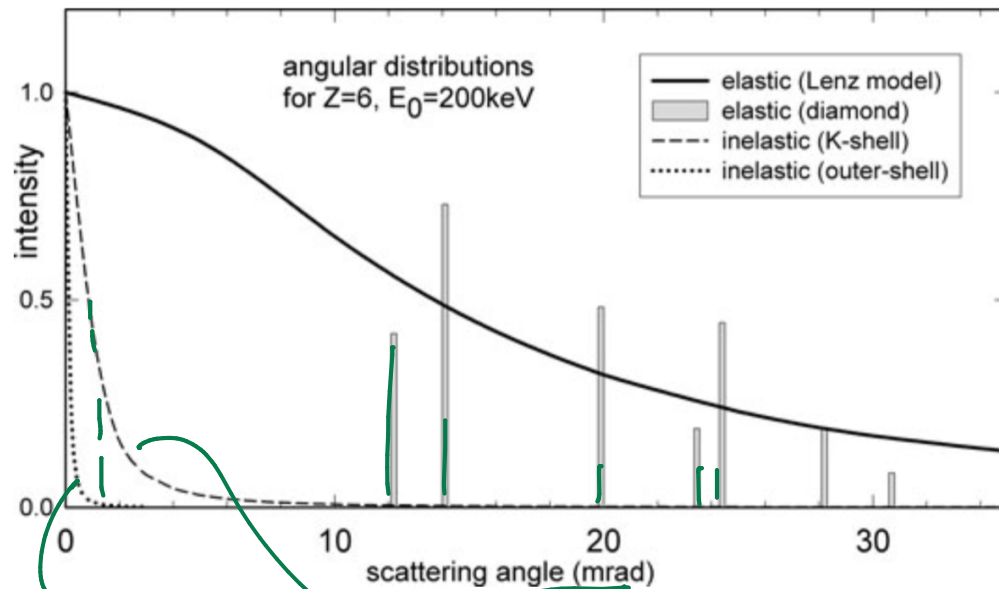
Compton dis. & inelastic scattering

- Inelastic scattering concentrated into much smaller angles than elastic scattering

- Characteristic angle for scattering: $\theta_E = \frac{\Delta E}{\gamma m_0 v^2} \sim \frac{\Delta E}{2E_0}$

Rule of Thumb

For carbon



$\Delta E : 800 \text{ eV}$

$E_0 : 200 \text{ keV}$

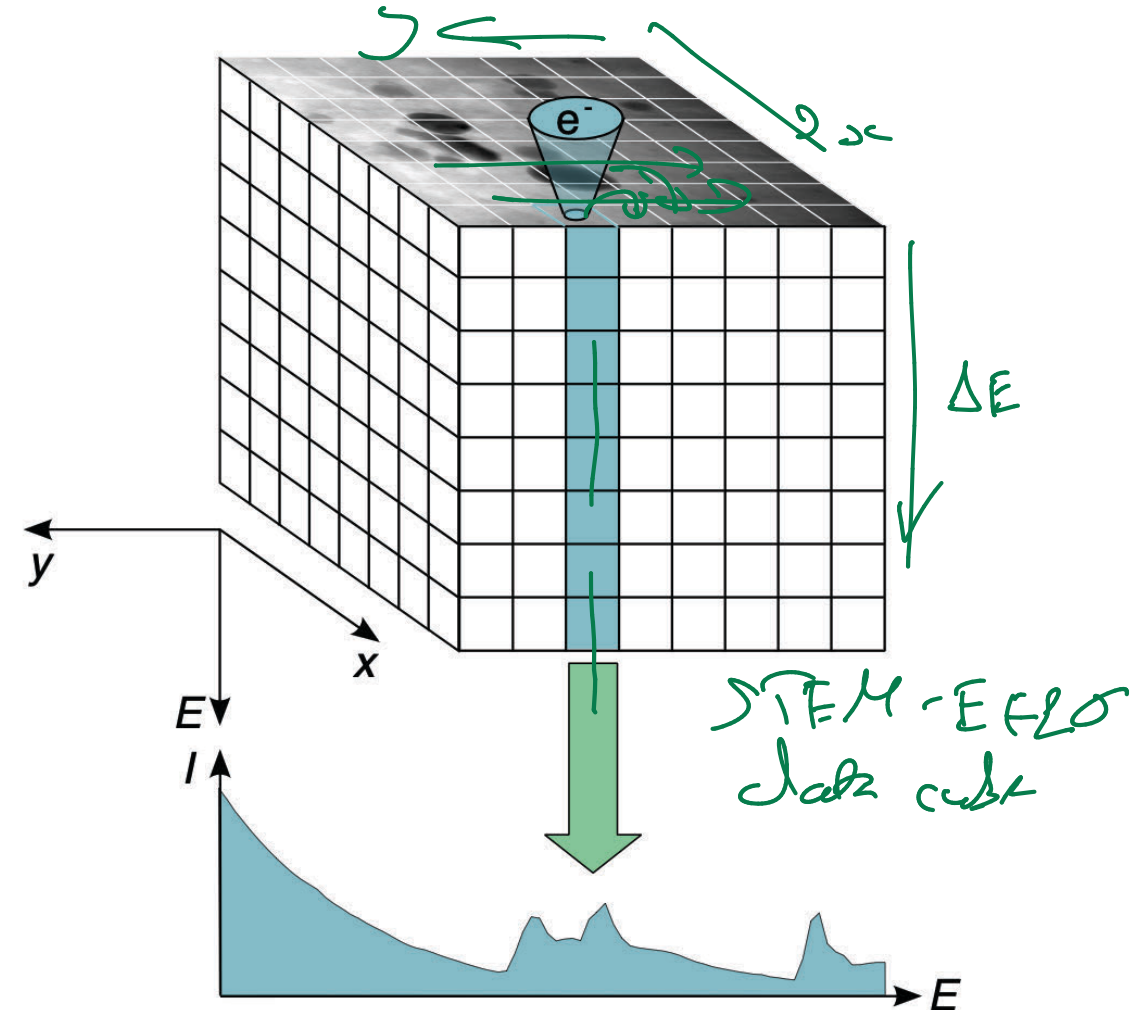
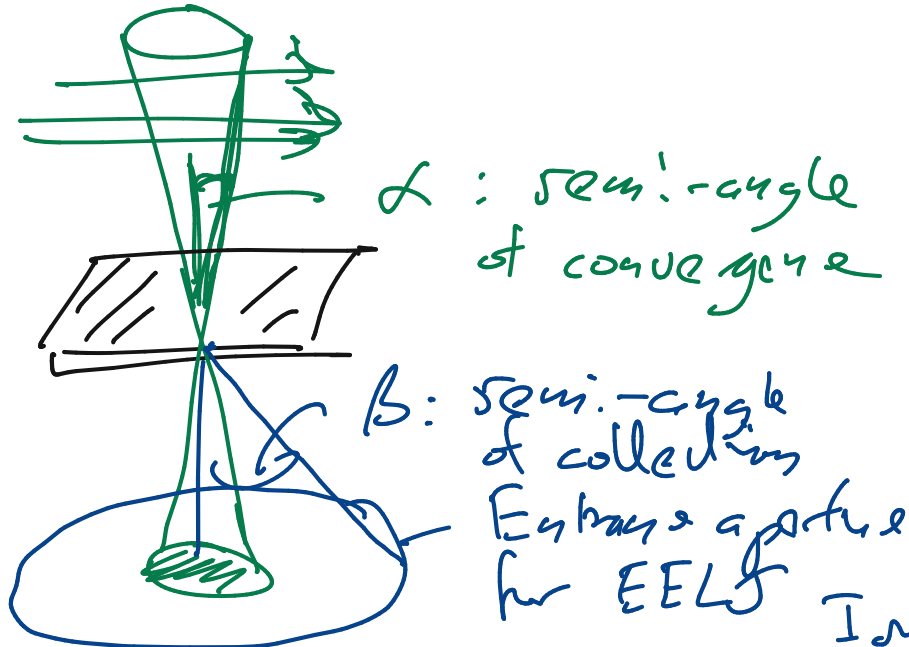
$\theta_E \sim 2 \text{ mrad}$

$\Delta E : 30 \text{ eV}$

$\Delta E : 300 \text{ eV}$

EPFL STEM-EELS spectrum imaging

- During STEM imaging, collect the *forward-scattered* electrons in the spectrometer entrance aperture
- Record 3D data cube with a spectrum for each probe position (x, y)



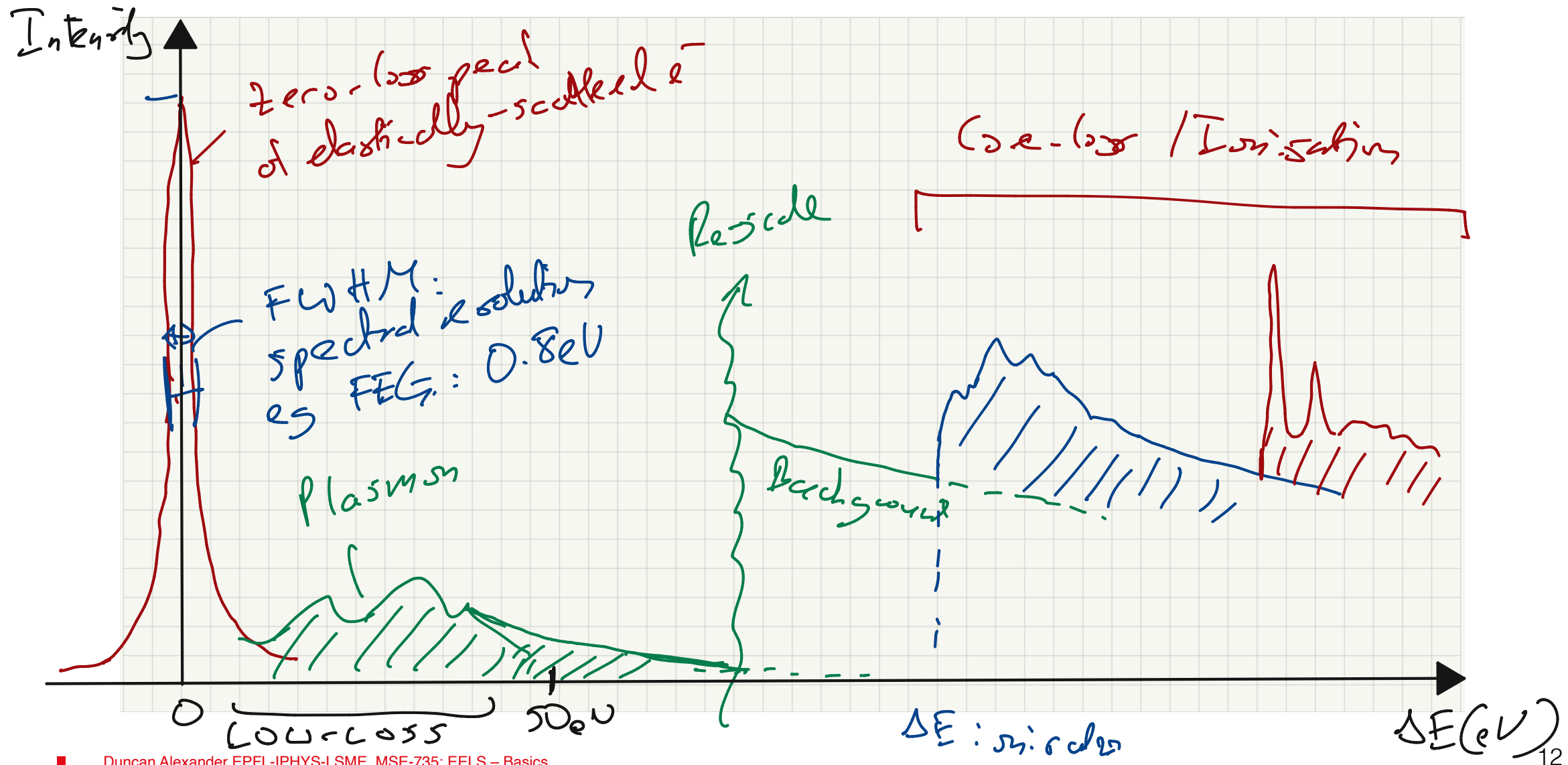
Irradiation : $\beta > \alpha$

Quant. EELS : $\beta \geq 2\alpha$

EPFL EELS basics: contents

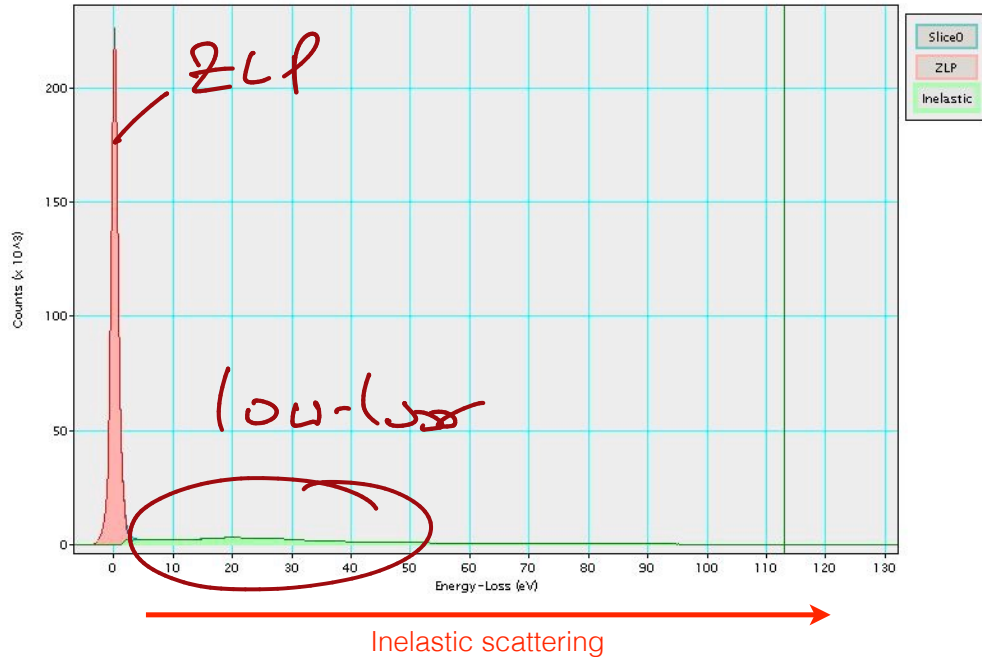
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EPFL Features of the EEL spectrum



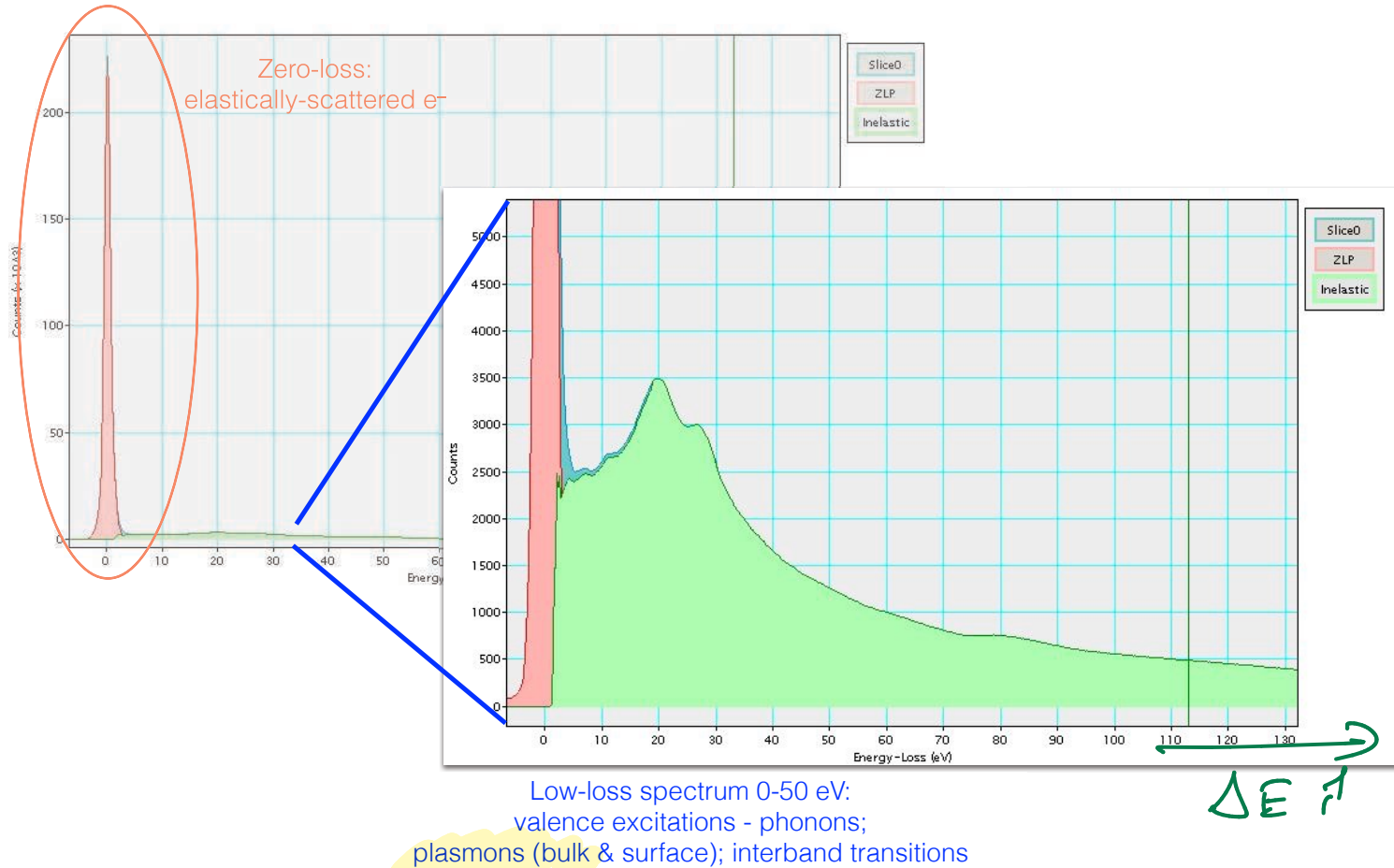
EPFL Features of the EEL spectrum

- Energy loss $> 0 \Rightarrow$ *Inelastic scattering*



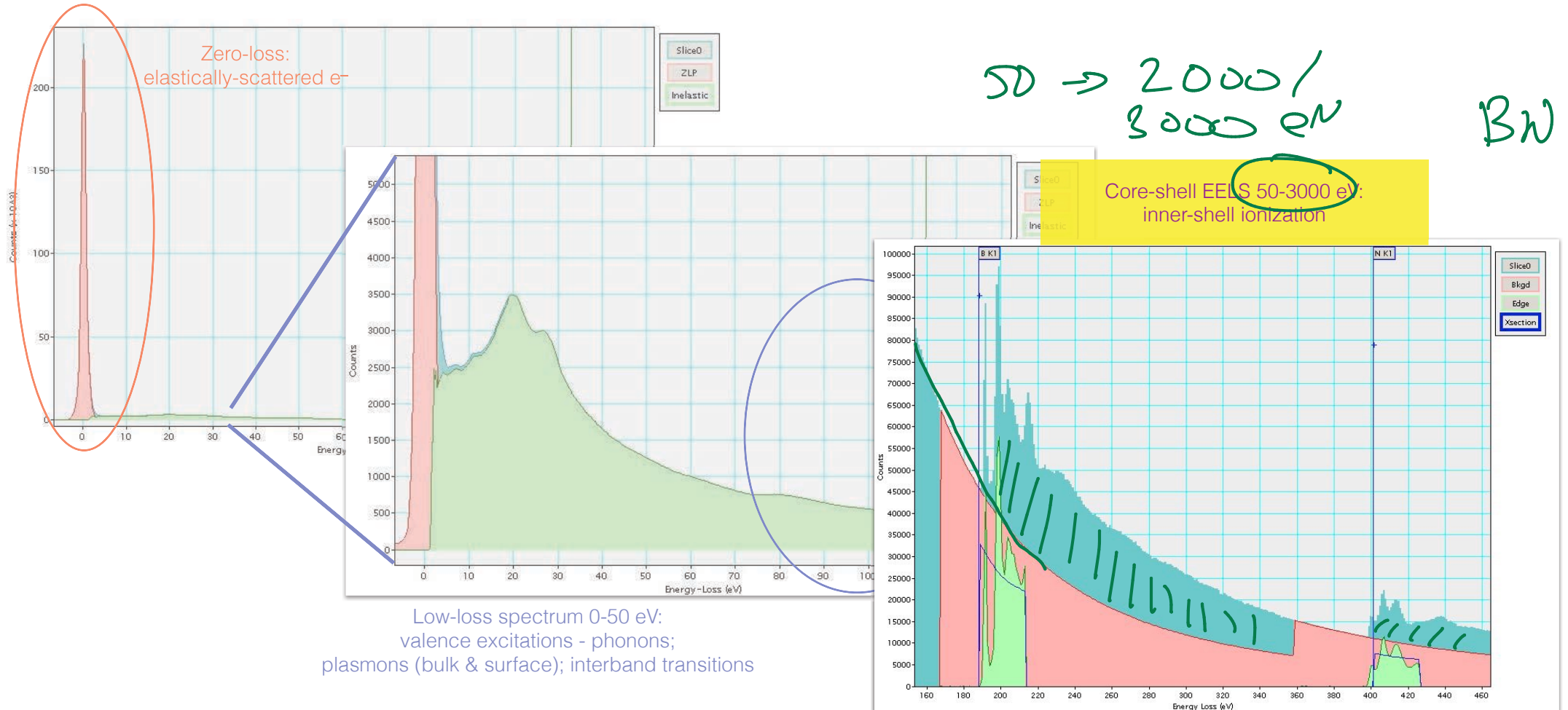
EPFL Features of the EEL spectrum

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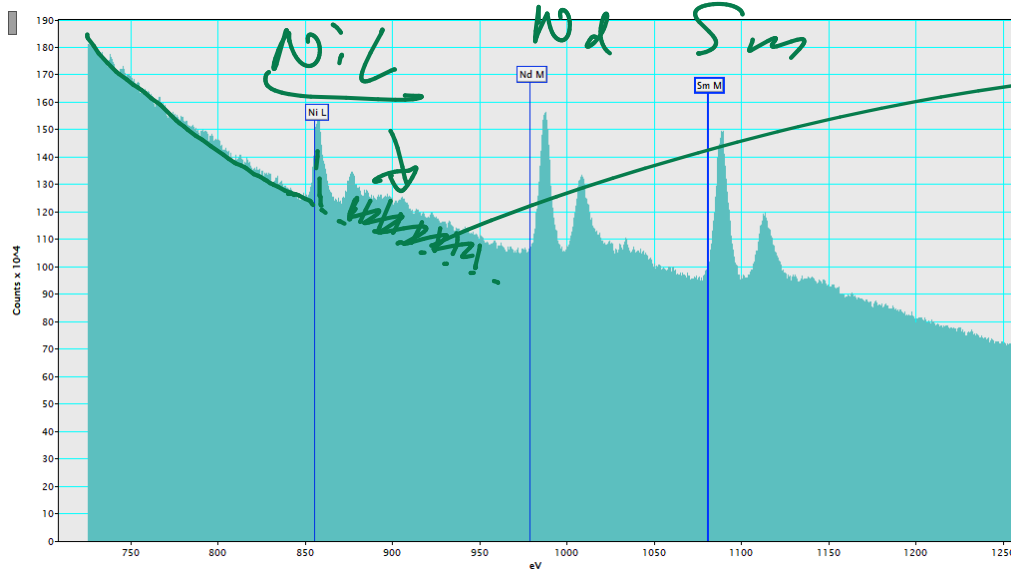
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EPFL Ionisation edge / “core-loss” analysis

- Elemental ionisation edges superimposed on exponentially decaying background (fit with power-law model)
- Signal intensity proportional to projected atomic concentration and elemental partial ionisation scattering cross-section $\Delta\sigma$

probability of inelastic scattering

(Nd, Sm)NiO₃ spectrum:

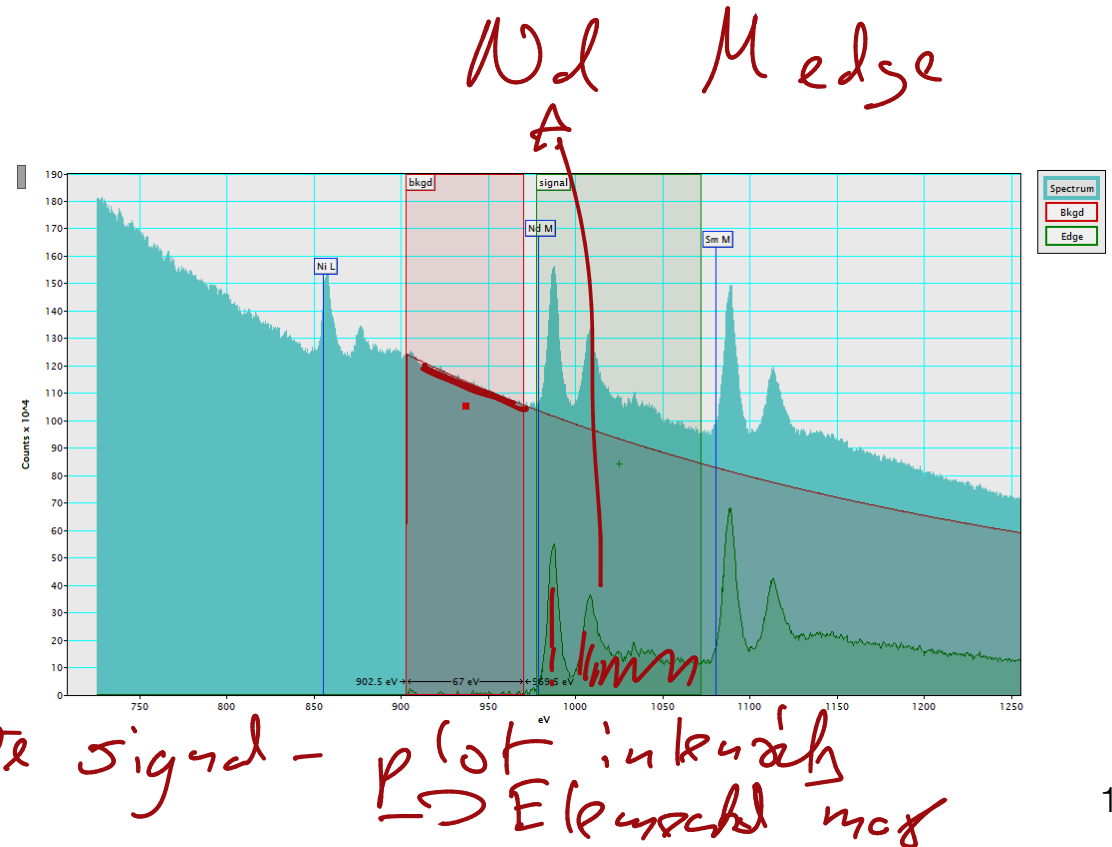
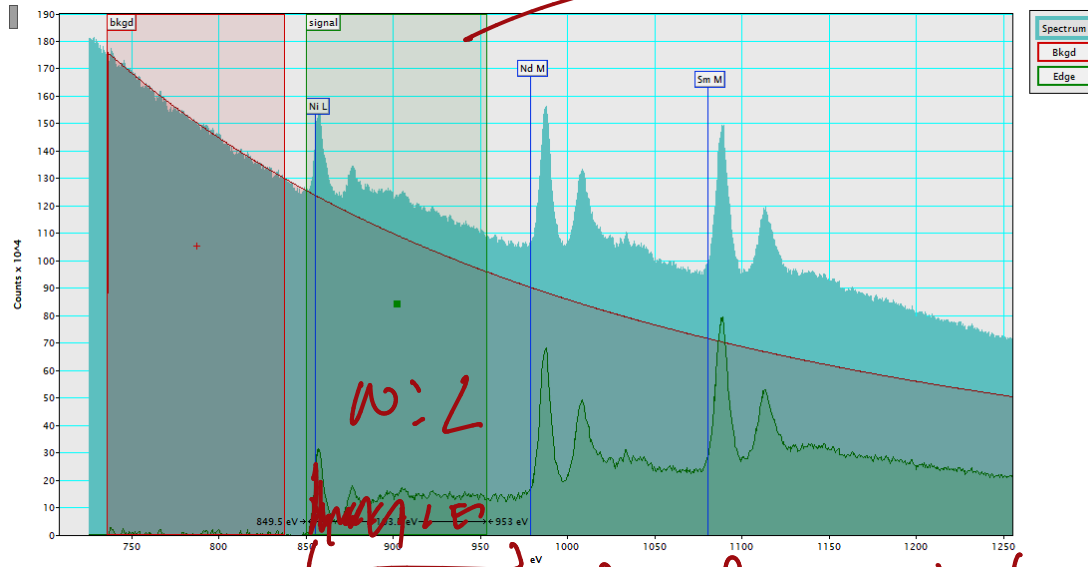


Signal intensity

EPFL Ionisation edge / “core-loss” analysis

- Elemental ionisation edges superimposed on exponentially decaying background (fit with power-law model)
- Signal intensity proportional to projected atomic concentration and elemental partial ionisation scattering cross-section $\Delta\sigma$

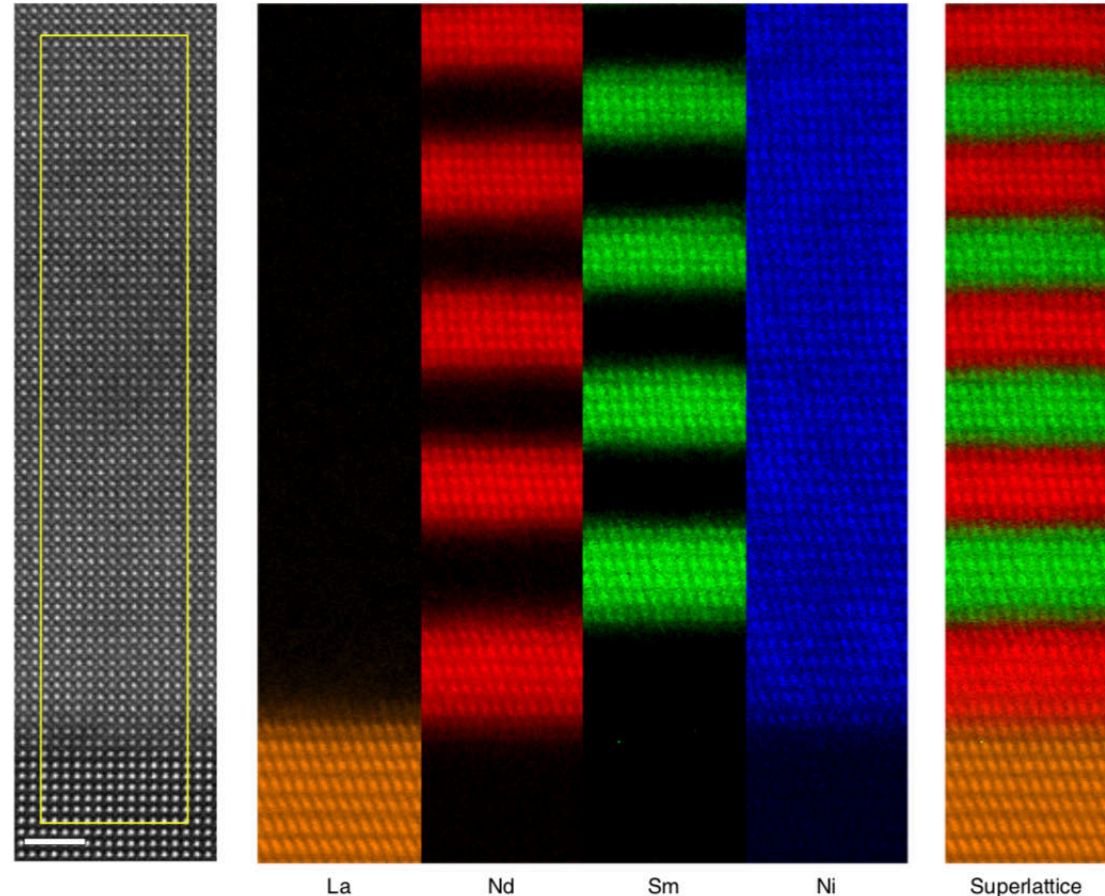
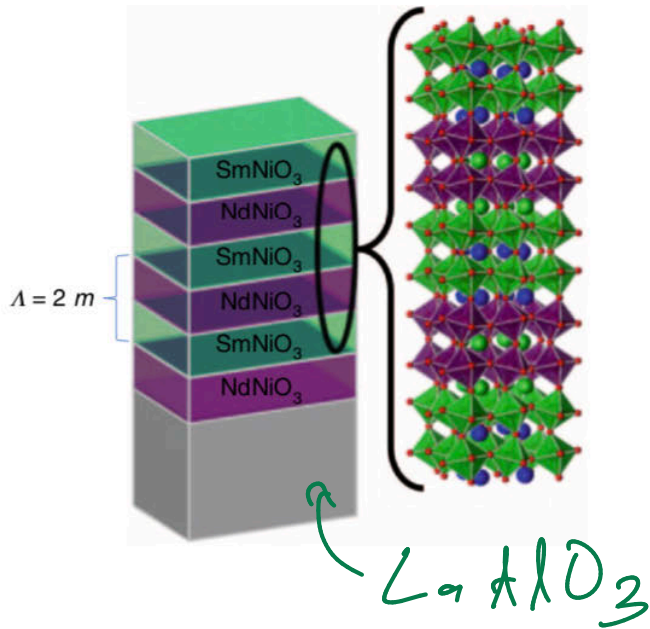
(Nd, Sm)NiO₃ spectrum:



EPFL Elemental mapping

- Produce elemental maps by plotting (x, y) integrated intensity in background-subtracted energy-loss “windows” selecting different ionisation edges

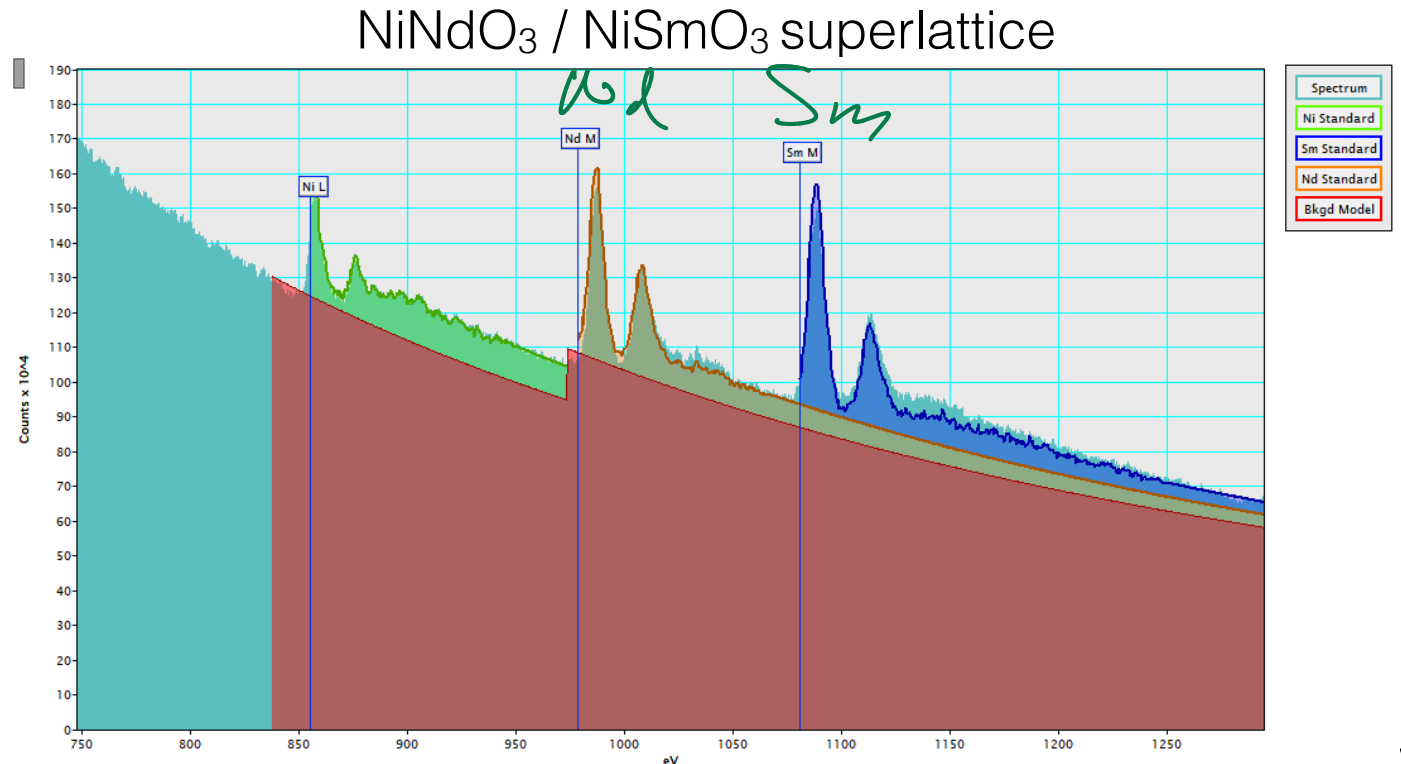
Example: NdNiO_3 / SmNiO_3 superlattice on LaAlO_3



EPFL Mapping: choose your elements wisely!

- First step: look at the EELS Atlas!
- What are the energy losses of your elements?
- Which ionisation edges can you fit on one spectrum?
- Do you have any overlaps?

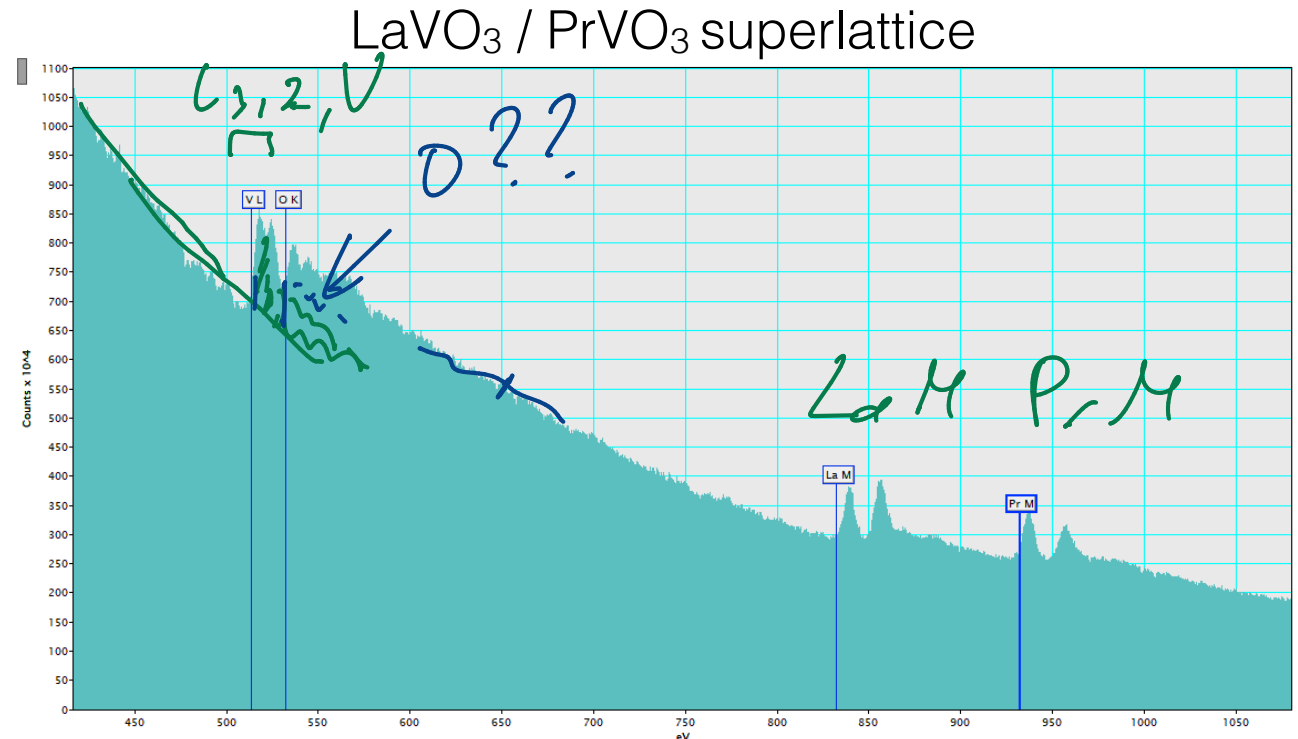
Model-based
fitting for Sm



EPFL Mapping: choose your elements wisely!

- First step: look at the EELS Atlas!
- What are the energy losses of your elements?
- Which ionisation edges can you fit on one spectrum?
- Do you have any overlaps?

$L_{2,3}$, O
↑
L: 525 eV
K: 532 eV
Cannot separate unique
signature of O K from
V L

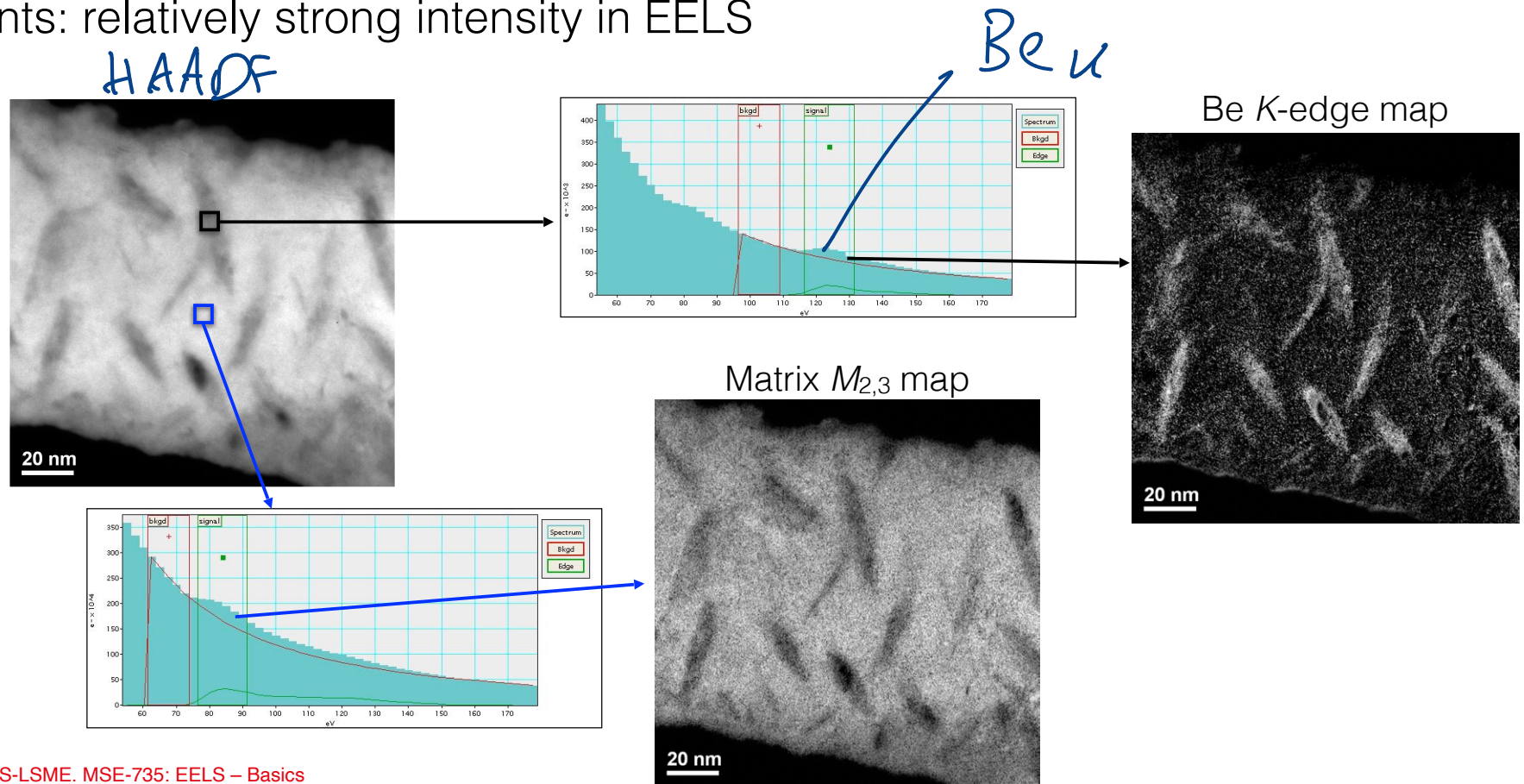


EPFL Benefits of EELS vs EDXS

- No artefacts from fluorescence/stray emission
- Physics and chemistry: ELNES, plasmons (see later)
- Light elements: relatively strong intensity in EELS

Example:
Be mapping

(EELS)



EPFL Elemental quantification

- Number of atoms per unit area N given by: $N = \frac{I}{j_0 \Delta\sigma}$

j_0 : incident current density

I : ionisation edge intensity

$\Delta\sigma$: sca. x-section

- Elemental percentages calculated using: $\frac{N_a}{N_b} = \frac{I_a}{I_b} \frac{\Delta\sigma_b}{\Delta\sigma_a} \equiv k\text{-factor} \sim \text{EDX}$

DM: calculate $\Delta\sigma$

- For good quantification, need knowledge and correct choice of convergence semi-angle α and EEL spectrometer collection semi-angle β

Accuracy $\sim 10-20\%$

- Example: BN measured in TEM mode ($\alpha \approx 0$) at 200 keV:

Δ : 100 mrad

- $\beta = 100$ mrad: 47 at.% B / 53 at.% N ✓

- $\beta = 0.5$ mrad: 23 at.% B / 77 at.% N ✗

β : 200 eV

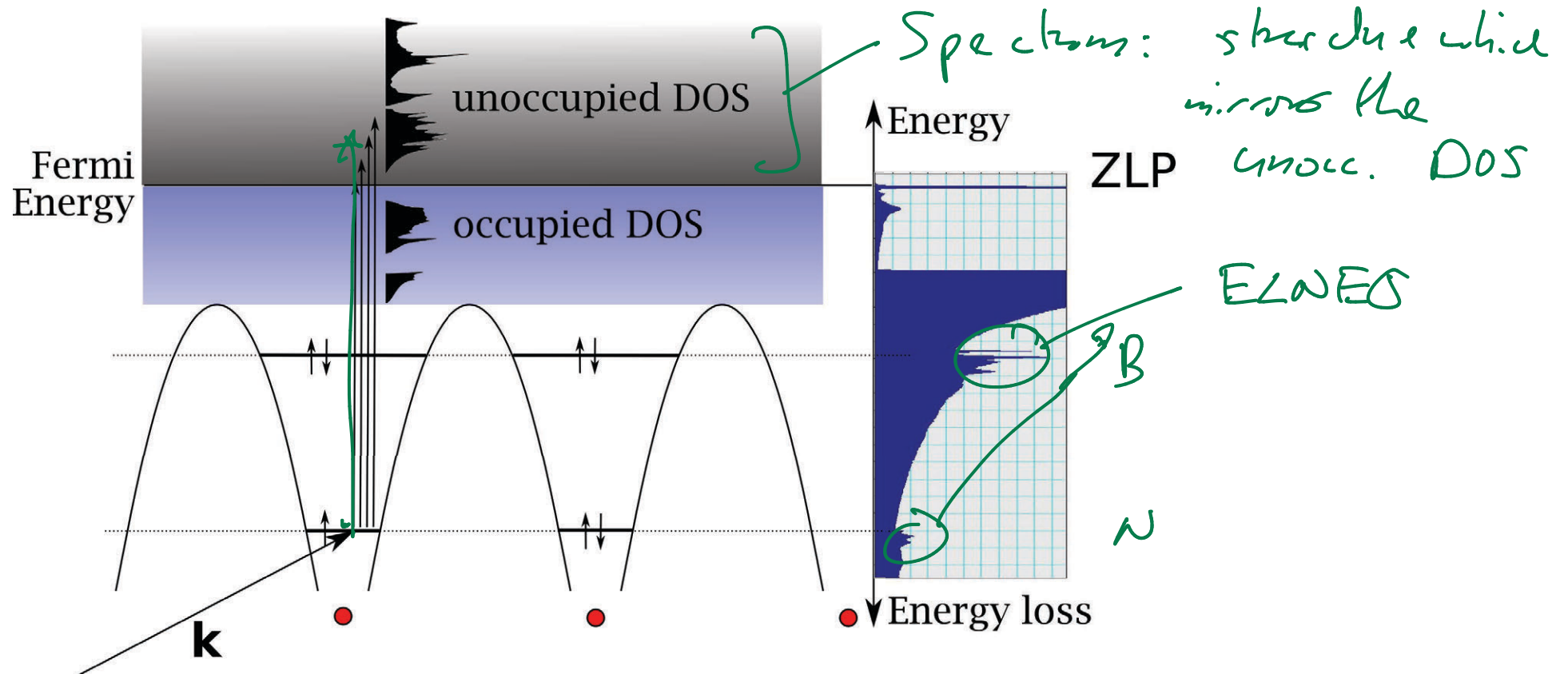
N : 400 eV

$\theta_E \sim 1$ mrad

→ Consider characteristic angle of scattering $\theta_E \sim \Delta E / 2E_0$
 Wrong β

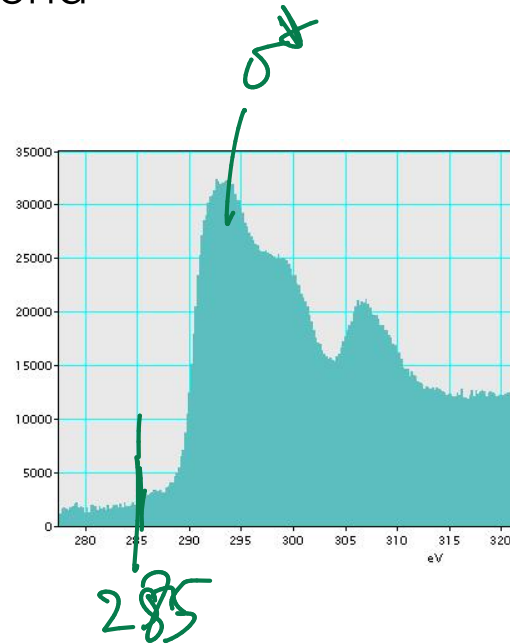
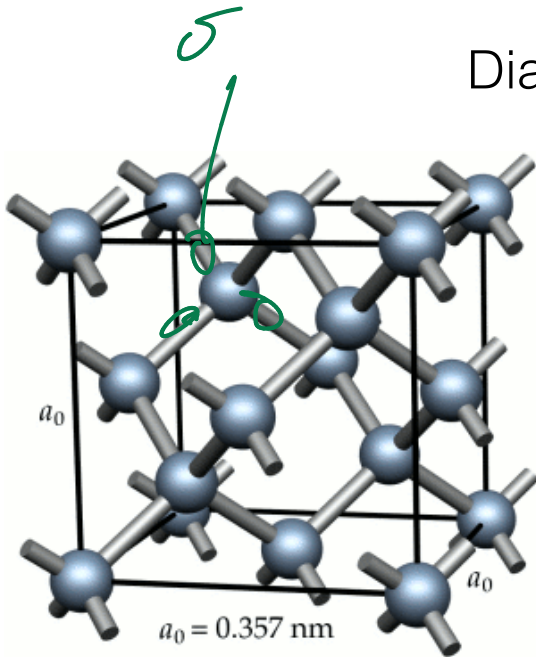
EPFL Energy-loss near edge structure (ELNES)

- Ionisation edge onsets show peaks related to unoccupied density of states (DOS)
- Fine structure comparable to X-ray absorption spectroscopy (XAS) data



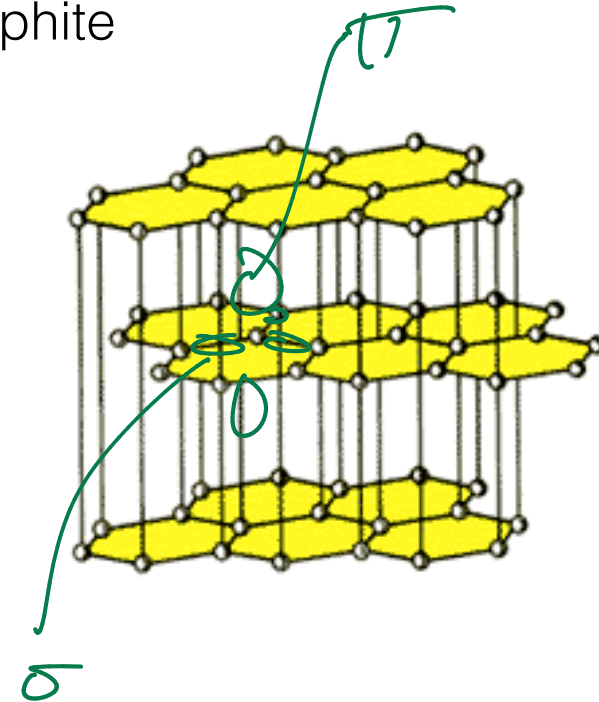
EPFL Core-loss fine structure σ^*

- Example: carbon *K*-edge



$$E_F = \frac{\pi^4}{\pi \sigma}$$

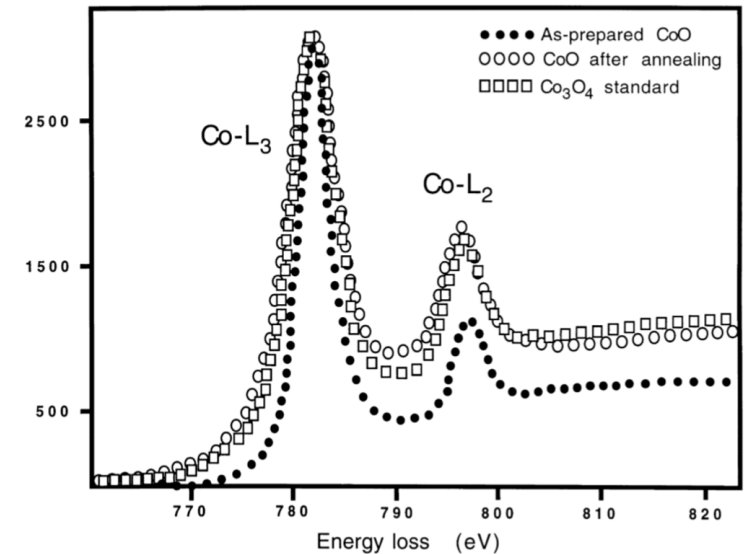
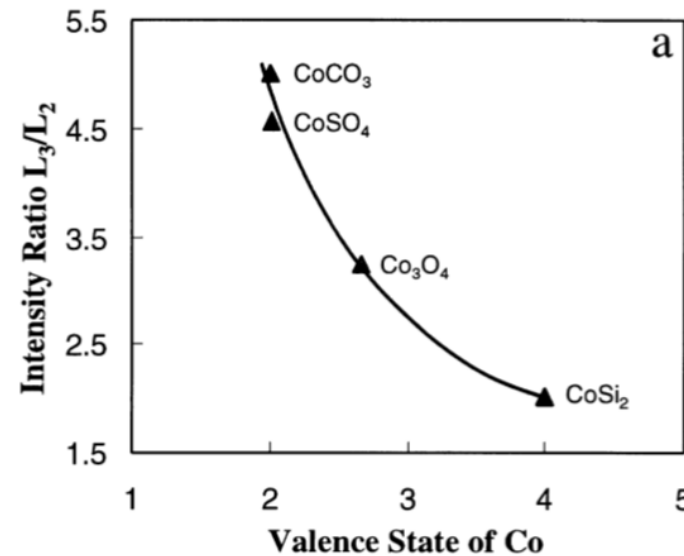
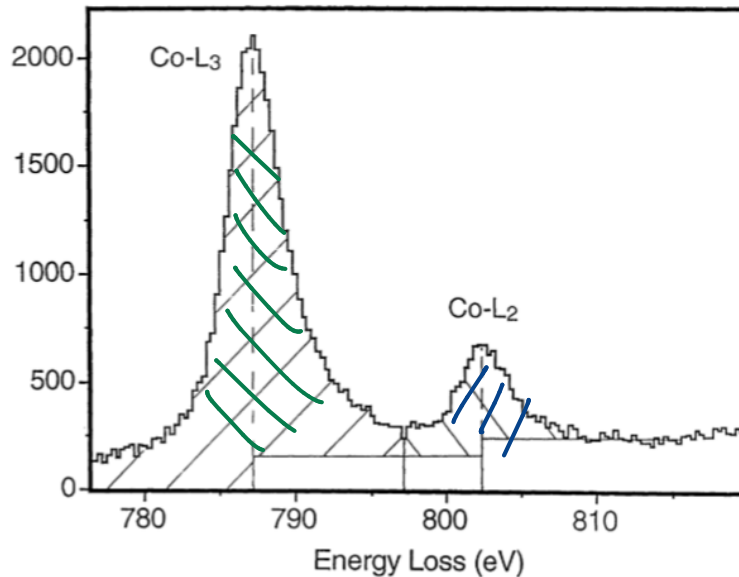
Graphite



EPFL “White line” analysis

- L_3, L_2 peaks

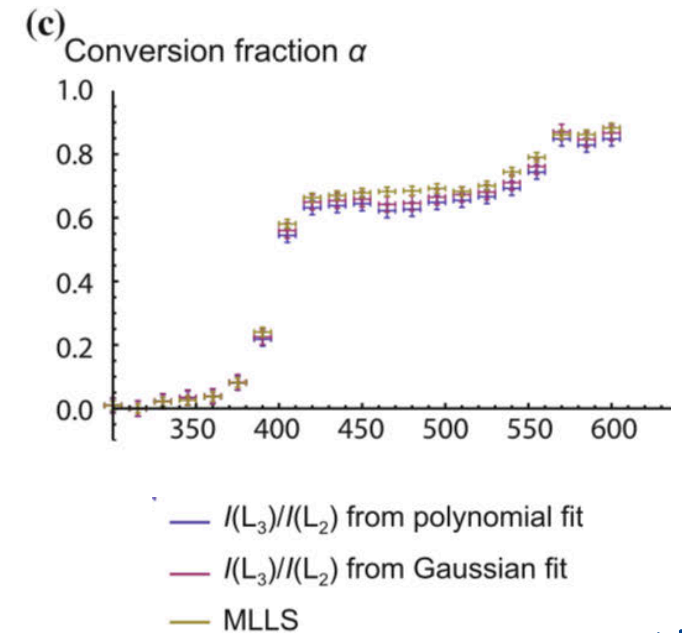
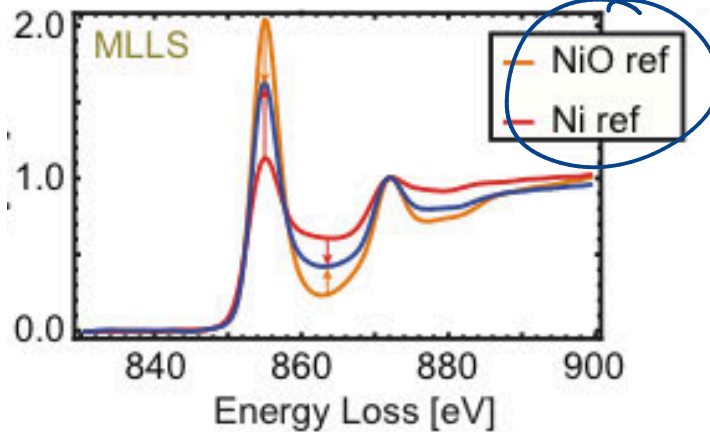
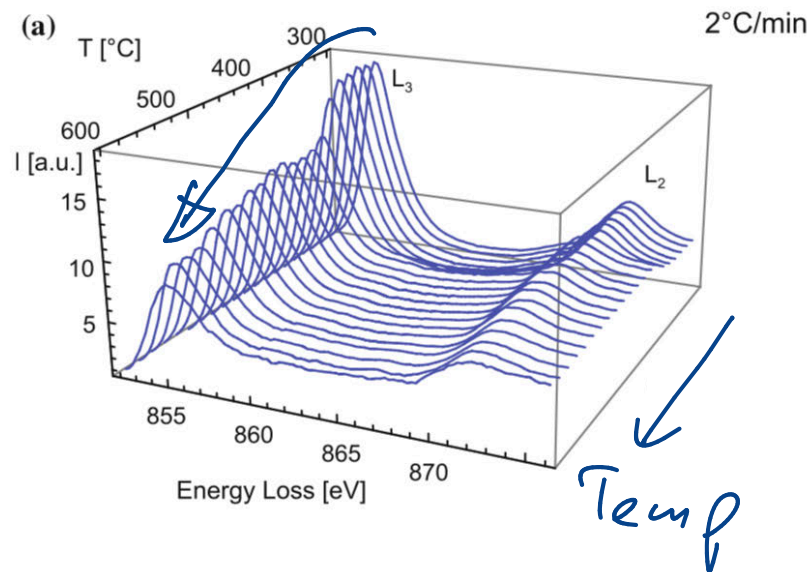
- ELNES peaks used to determine valence/oxidation state e.g. of transition metals
- Example: Co oxidation state



Wang et al. Micron **31** 571 (2000)

EPFL “White line” analysis

- ELNES peaks used to determine valence/oxidation state e.g. of transition metals
- Example: Ni oxidation state during *in-situ* reduction of NiO



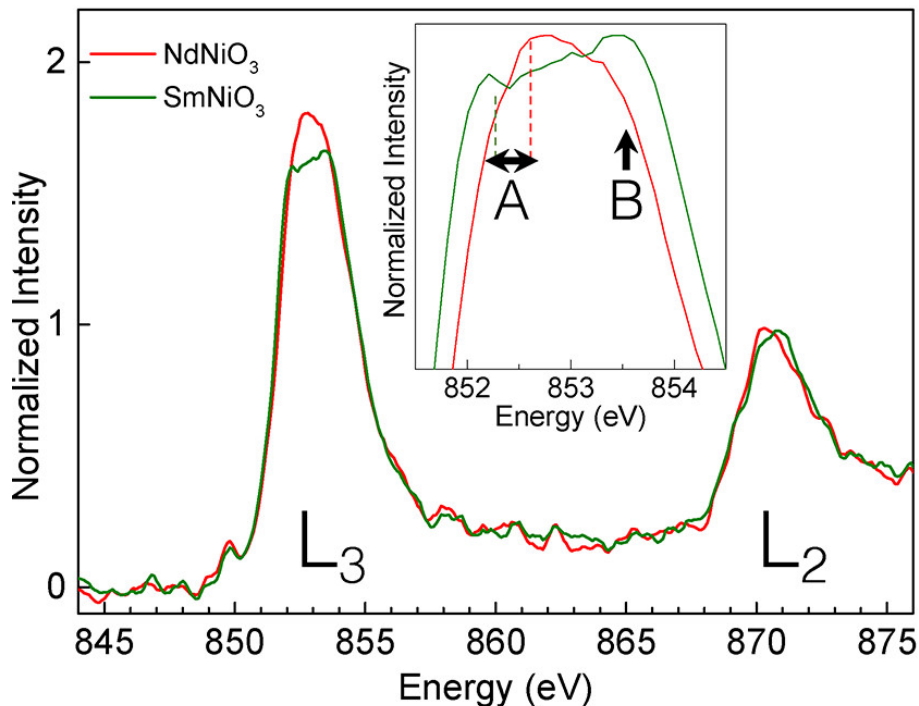
ELNES: can simulate with e.g. DFT + code “Wien 2k”

Jeangros et al. J. Mater. Sci. **48** 2893 (2013)

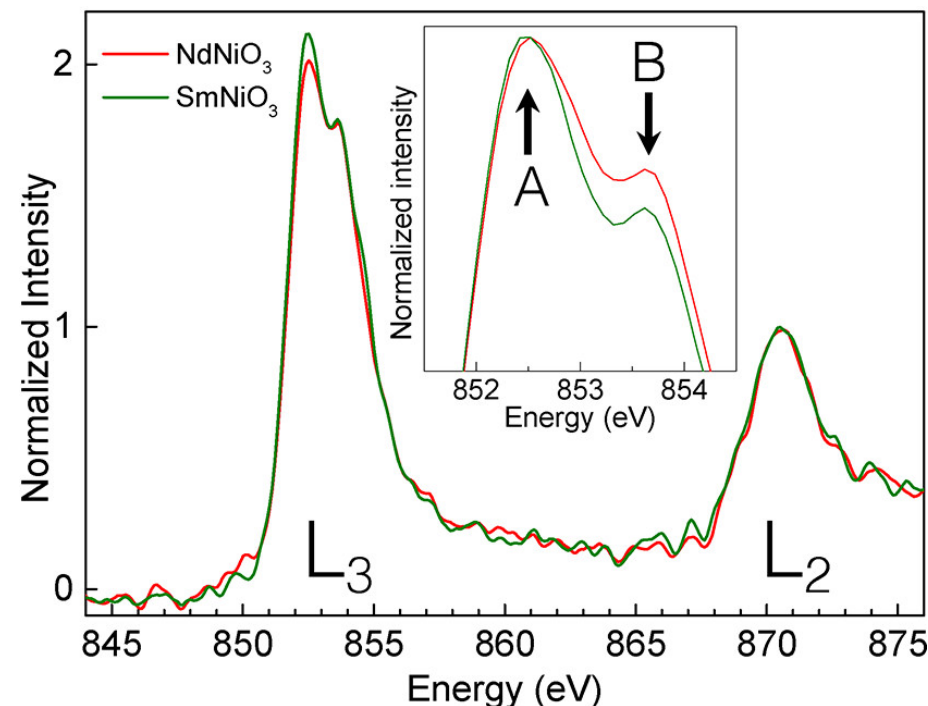
EPFL Probing electronic states in nickelates

- Small modulations in EELS Ni L_3 peak used to measure electronic state

30/30 lattice: NdNiO_3 metallic; SmNiO_3 insulating



5/5 lattice: both NdNiO_3 and SmNiO_3 metallic

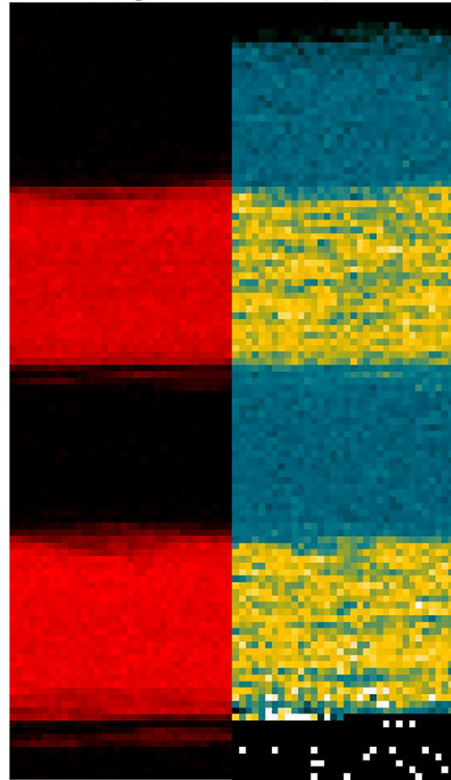


EPFL Probing electronic states in nickelates

- Map Ni L_3 peak A position $\Rightarrow$ electronic state mapping

30/30 lattice NdNiO_3 SmNiO_3

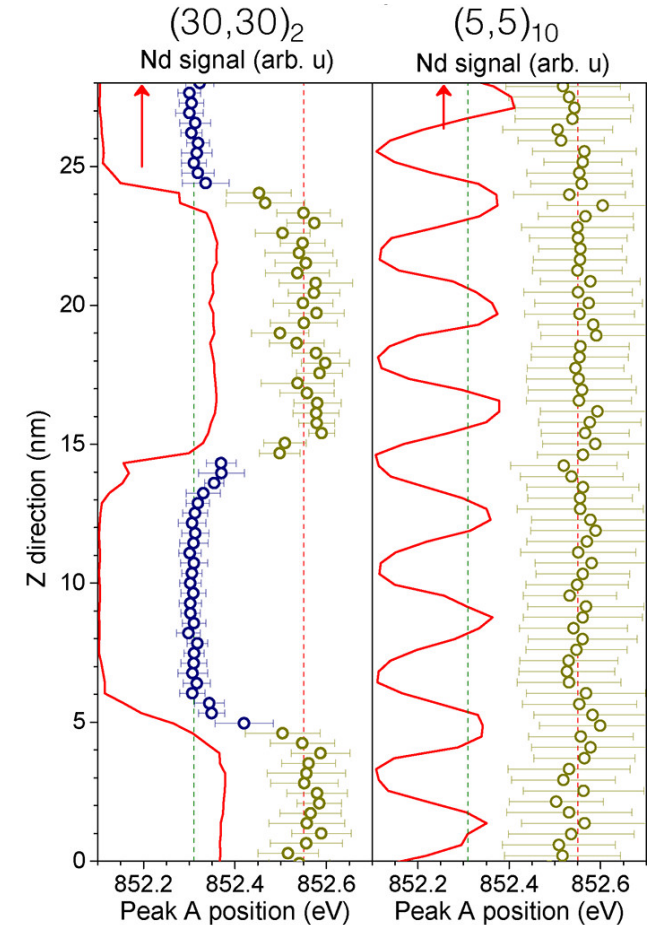
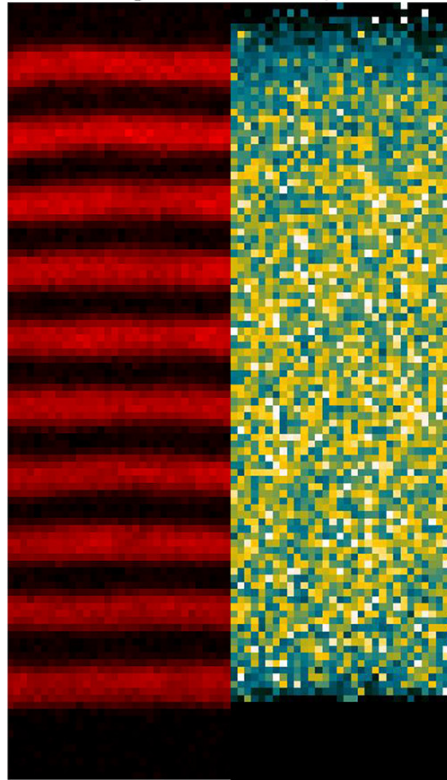
Nd signal Peak position



852.0 eV 852.8 eV

5/5 lattice: NdNiO_3 SmNiO_3

Nd signal Peak position

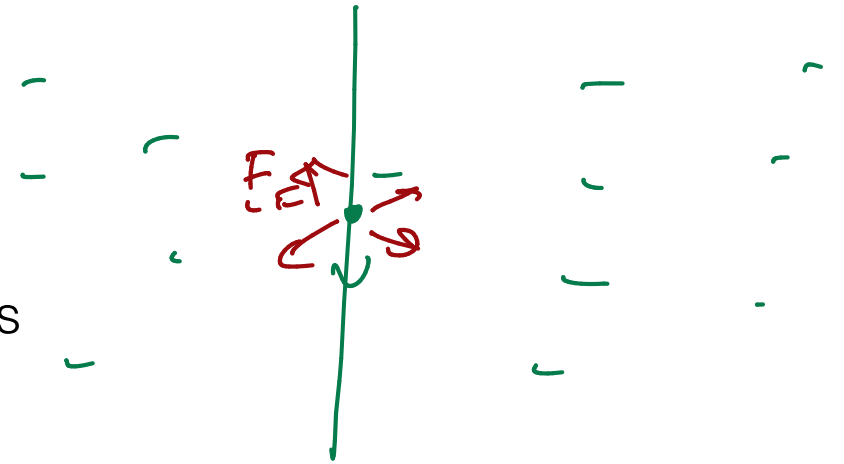


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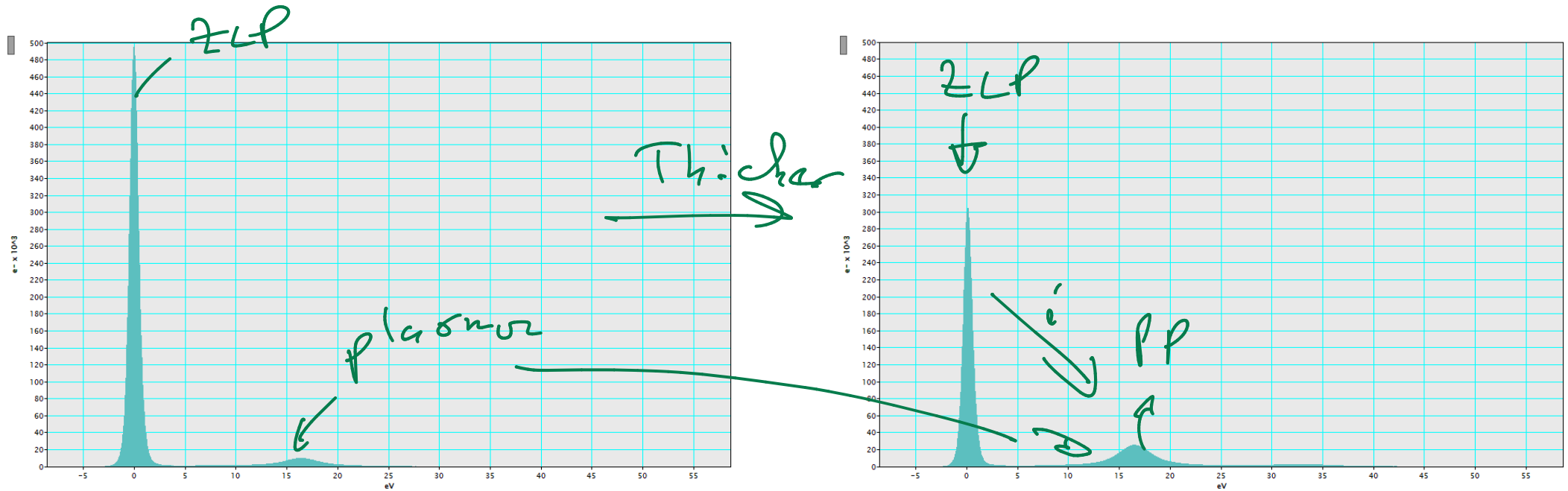
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EPFL Low-loss EELS

- For $\Delta E \sim 1\text{--}50$ eV: excitation of plasmons
- Volume/bulk plasmon: oscillation of valence electrons



Example low-loss: crystalline Si

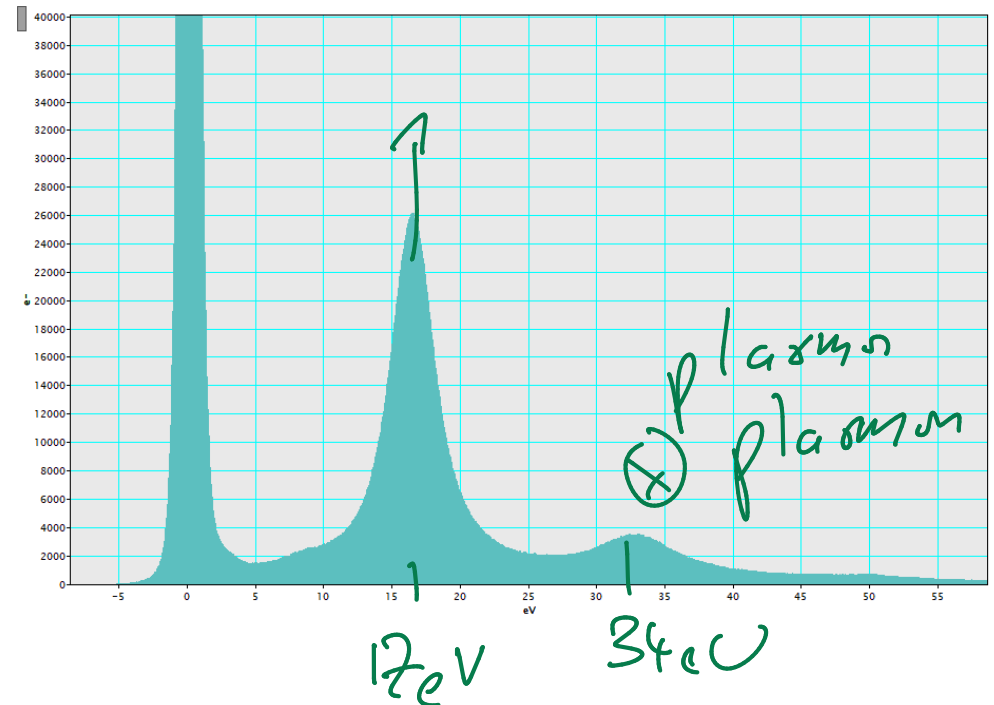
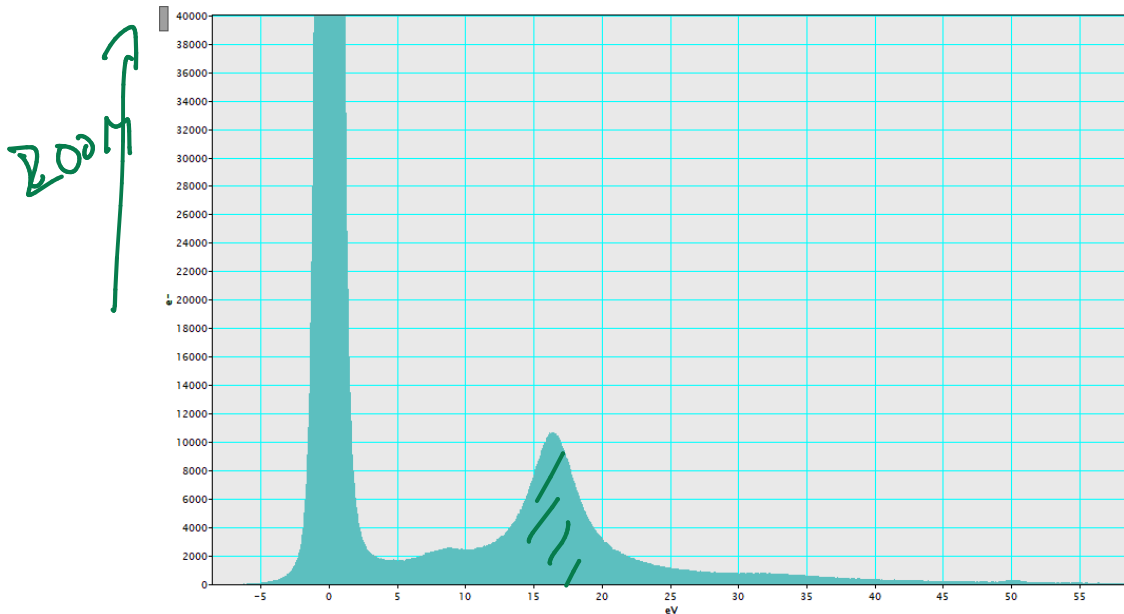


EPFL Low-loss EELS

- For $\Delta E \sim 1\text{--}50$ eV: excitation of plasmons
- Volume/bulk plasmon: oscillation of valence electrons

Free e^- model
(Drude model)
→ Lorentzian p.p.

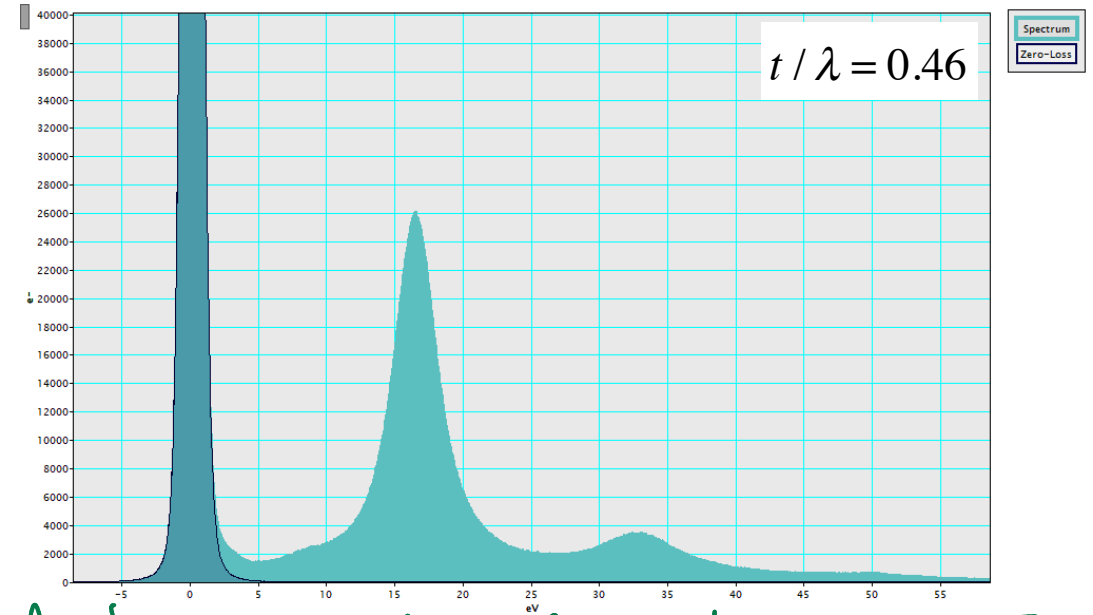
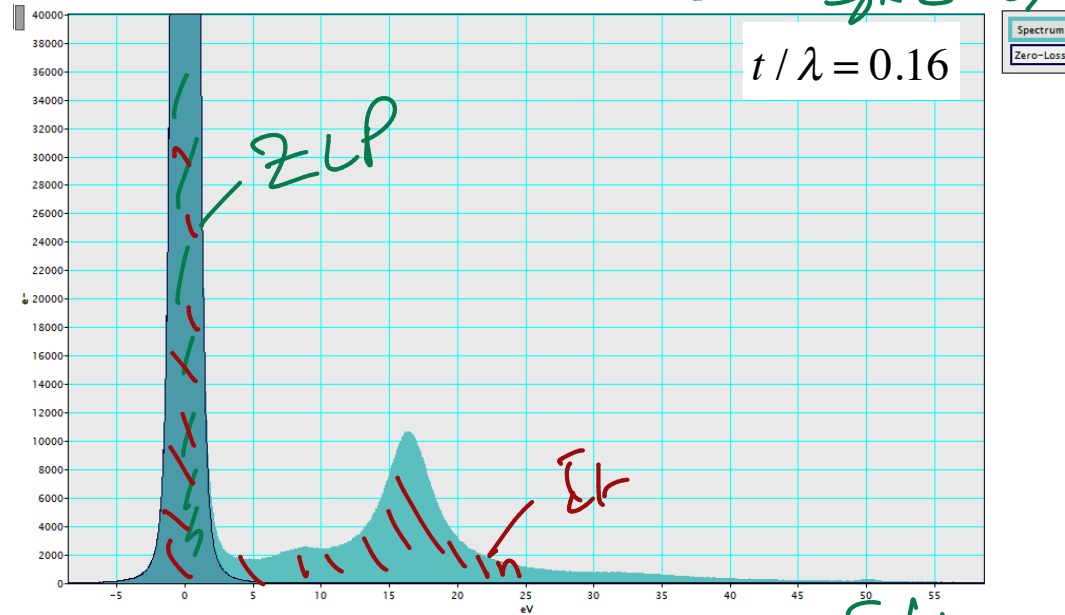
Example low-loss: crystalline Si



EPFL Multiple scattering

Sample thickness t

- As specimen thickness increases, have multiple scattering
- Inelastic scattering mean free path: λ $\rightarrow$ Av. distance between inel. scattering events
- From Poisson statistics: $t/\lambda = \ln(I_t/I_0)$
 $\hookrightarrow$ Int. spectrum $\uparrow$ Int. ZLP



Elt. analysis with $0.3 \lesssim t/\lambda \lesssim 0.7$

EPFL Sample thickness measurement

- By calculating λ the sample thickness t can be estimated

- Two routines in Digital Micrograph:

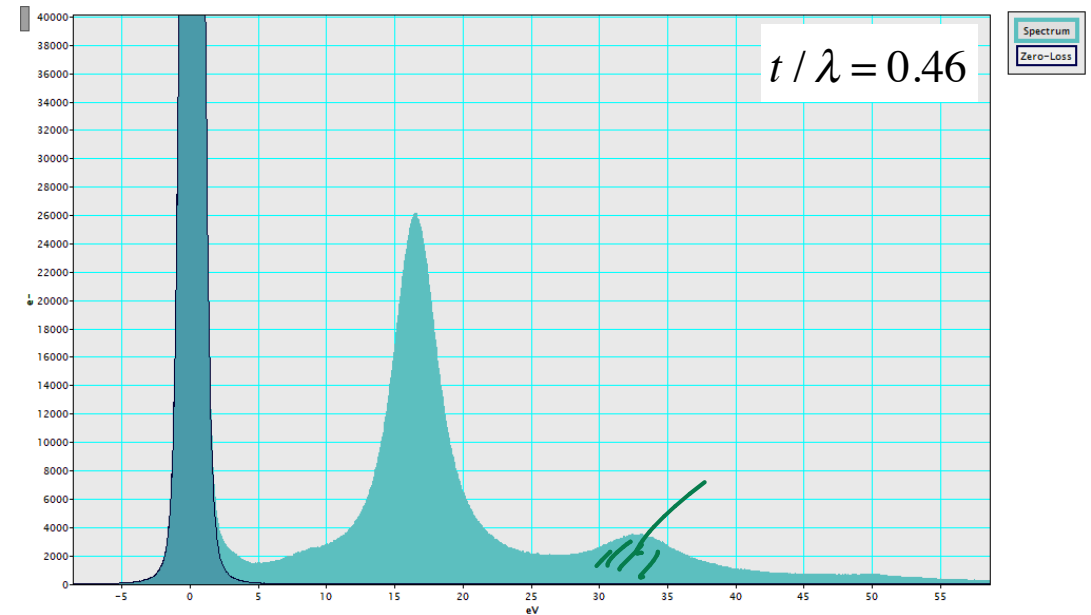
- Kramers-Kronig sum rule
- Log-ratio (absolute) – Bethe sum rule

Relative index
→ Av. Z

$\lambda \sim 100 \text{ nm}$

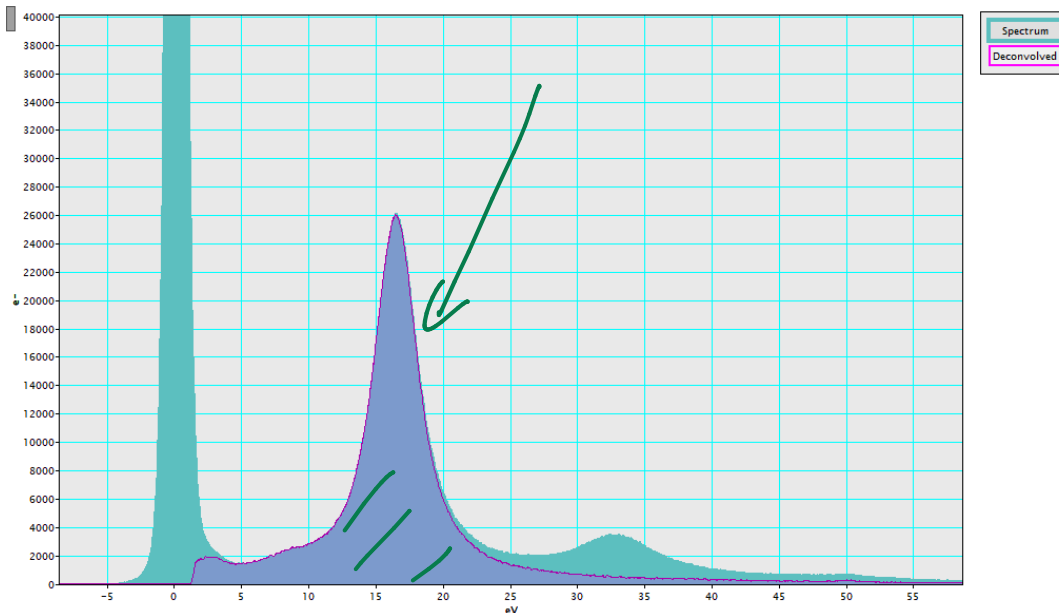
- Accuracy $\sim \pm 5\text{--}10 \text{ nm}$

Need α , β



EPFL Spectral deconvolution

- Deconvolution can be used to retrieve the *single scattering distribution* (SSD)
- Core-loss spectra: use Fourier-ratio deconvolution (needs low-loss spectrum)
- Low-loss spectra: use Fourier-log deconvolution:

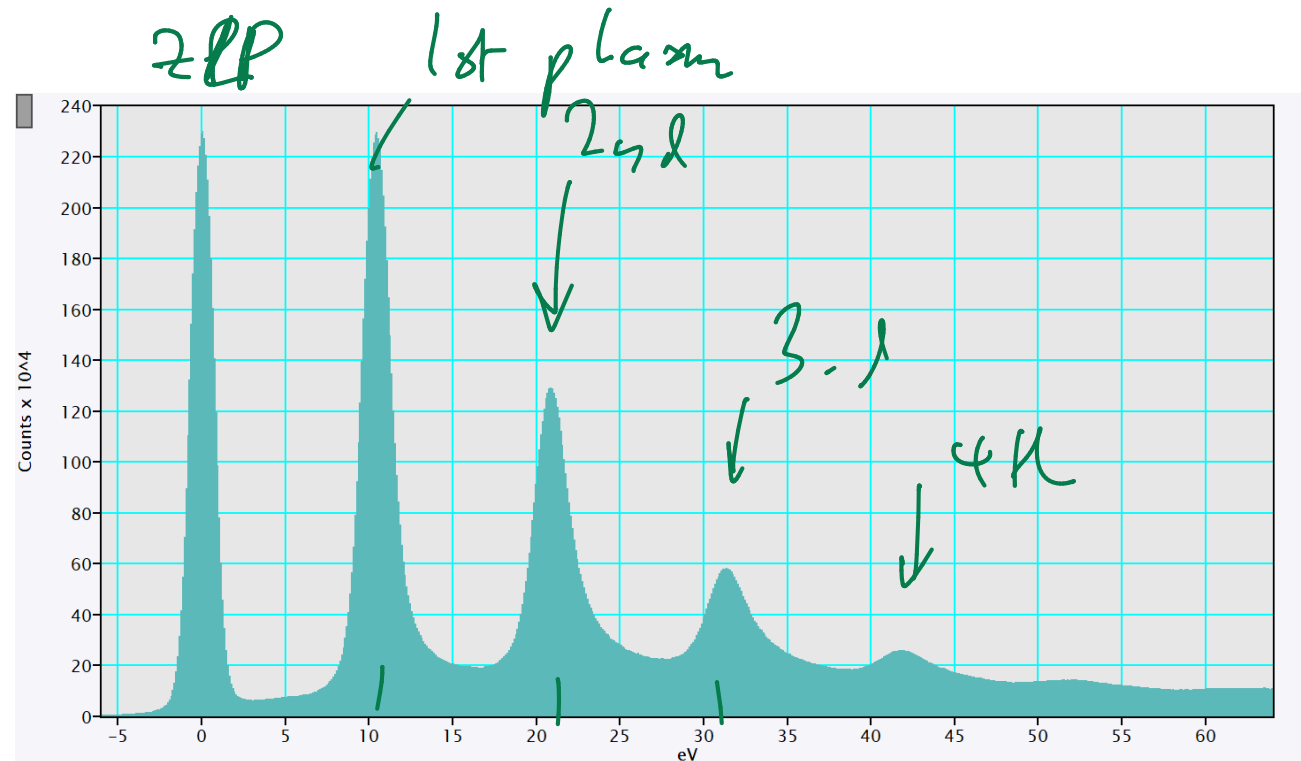
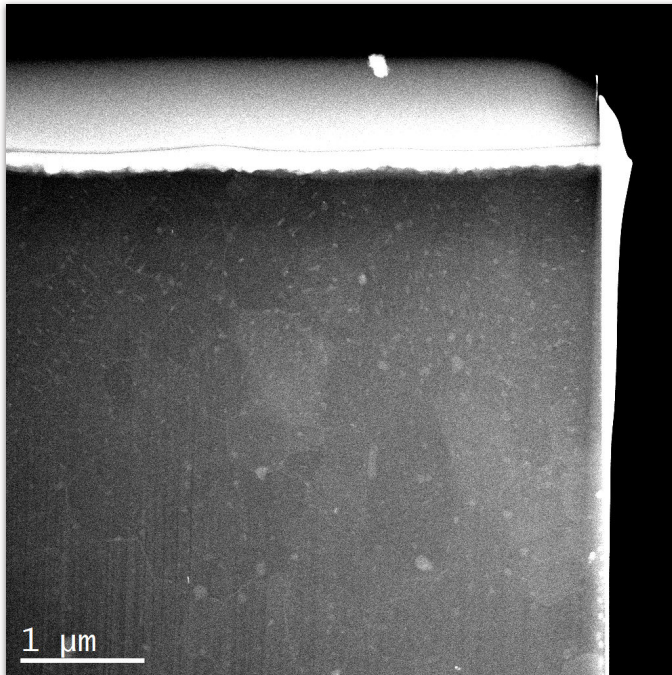


- Intensity of SSD: $\Gamma(\omega) \propto \text{Im} \left\{ -\frac{1}{\epsilon(\omega)} \right\}$
low loss

$$\Sigma = \Sigma' + i\Sigma''$$

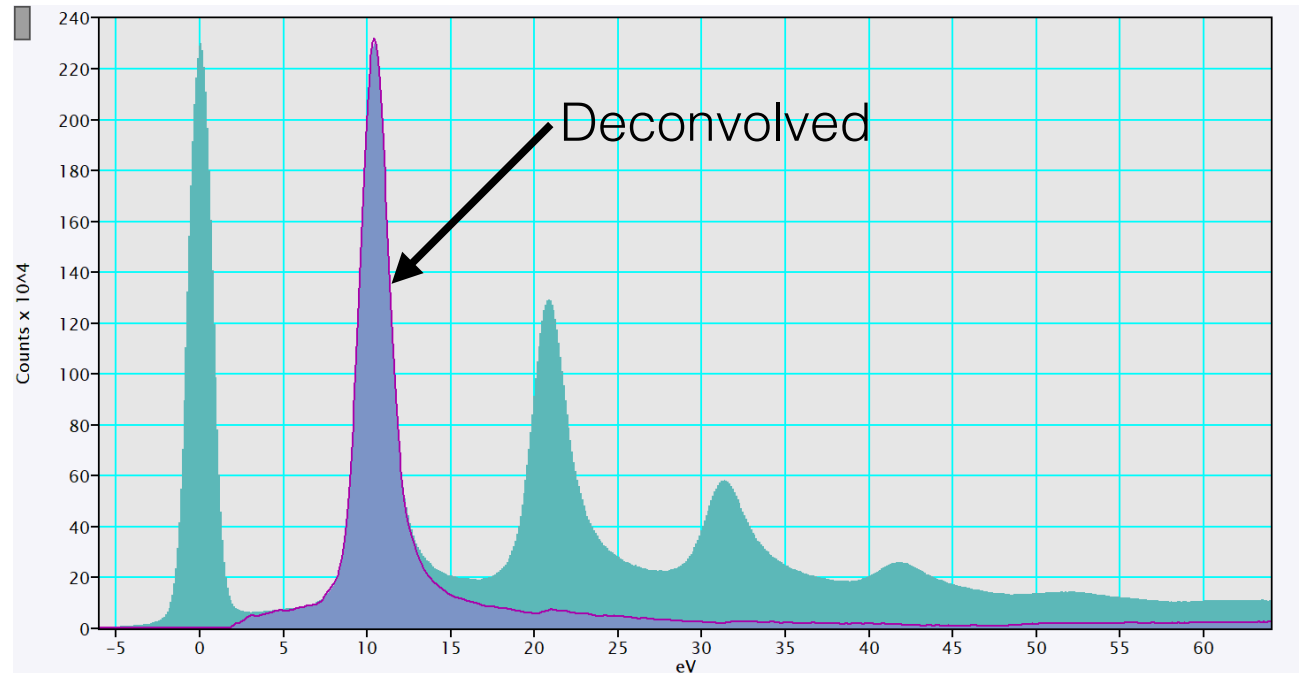
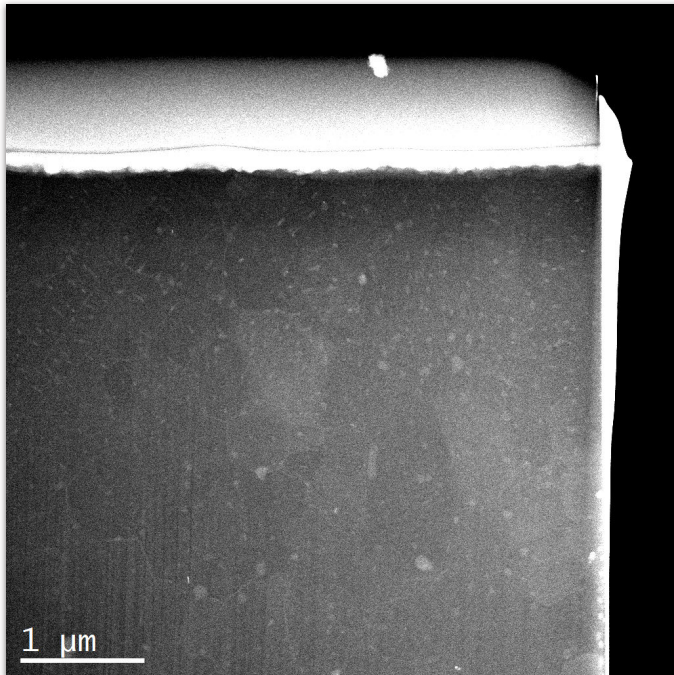
EPFL Multiple scattering: Mg sample

- Thick sample: $t / \lambda \approx 2.3$
- Well-defined plasmon peak (free electron gas)
- Multiple orders of plasmon peak excitation



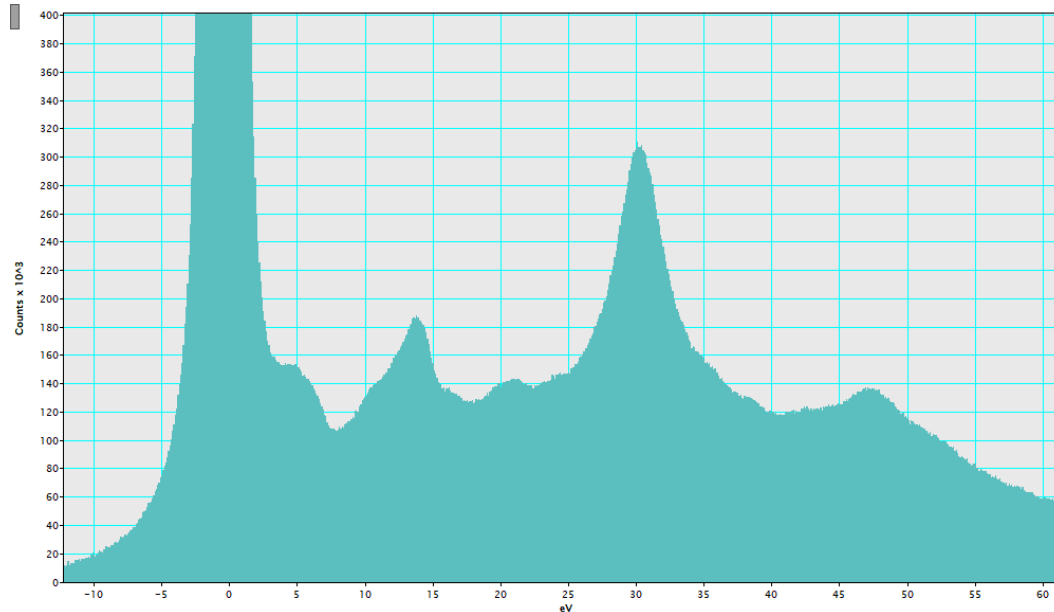
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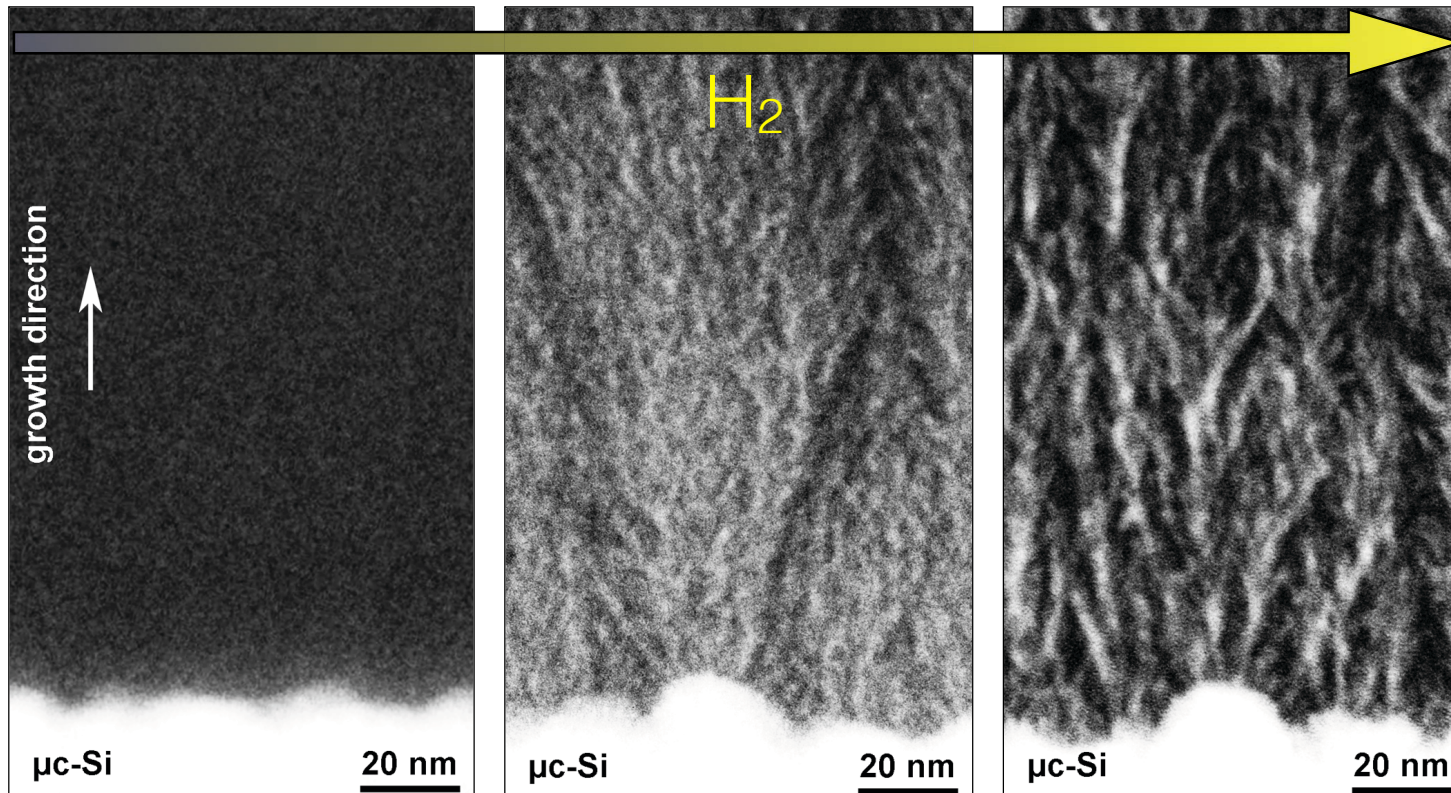


- As well as bulk plasmons, can have surface plasmons, Cherenkov losses
- Bulk plasmon region can also show single electron excitations
⇒ Low-loss spectrum has features related to phase electronic structure

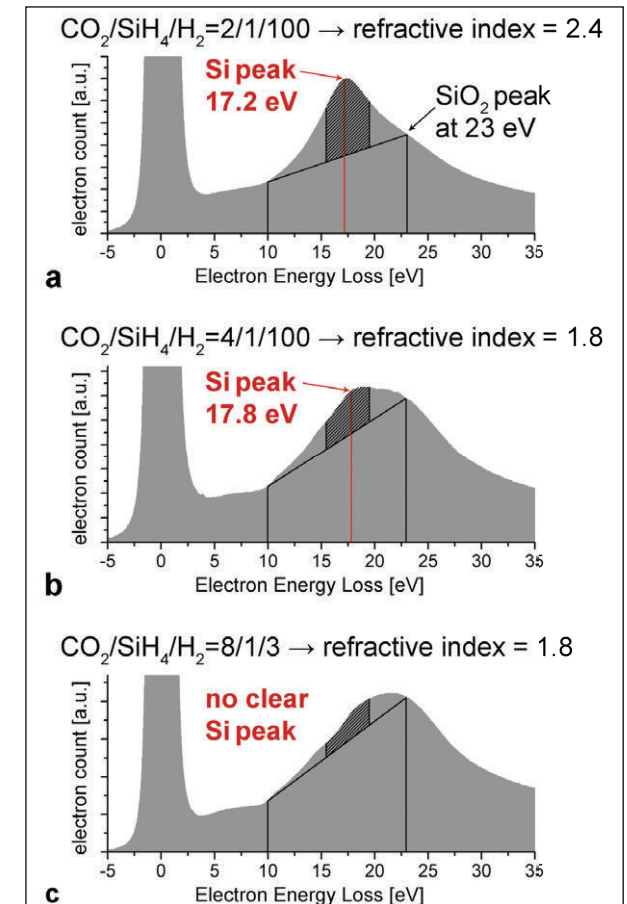
SrTiO₃ low-loss:



- Use plasmon peak to map elemental Si nano-filaments in SiO_x thin films



- Increasing H_2 plasma $\Rightarrow$ increased phase separation

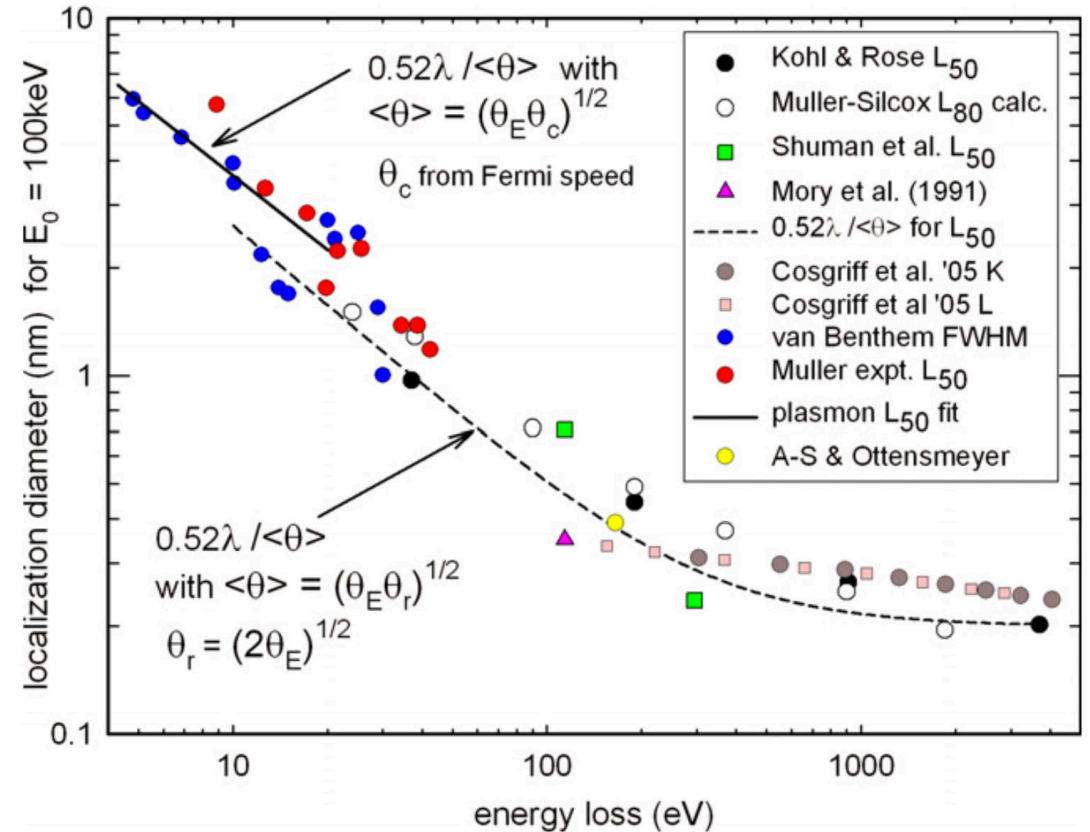


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EPFL EELS spatial resolution

- Attainable spatial resolution of EELS signal depends on the nature of the scattering process
- Decreasing energy loss ΔE
 $\Rightarrow$ increasing spatial *delocalisation*
- (Exception: acoustic phonon excitations with high momentum transfer)



Egerton Rep. Prog. Phys. **72** 016502 (2009)

EPFL References

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